

# **Wide-Bandgap Semiconductors for Power Electronics**

**Bob Kaplar**

**Sandia National Laboratories**

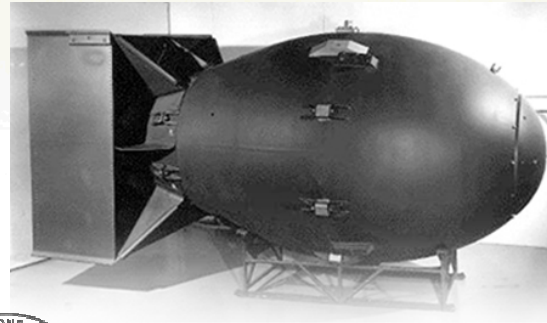
**Presented at KLA-Tencor**

**April 12, 2013**

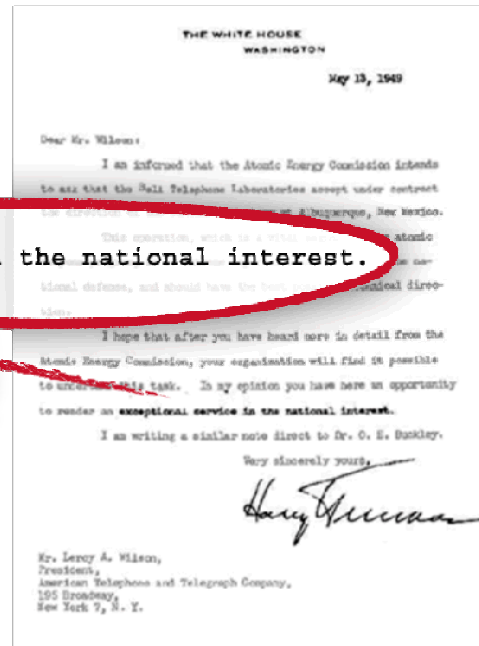


Parts of the work presented were supported by the DOE Office of Electricity, Energy Storage Program (Dr. Imre Gyuk) and GaN Initiative for Grid Applications (Dr. Mike Soboroff). Sandia National Laboratories is a multi-program laboratory managed and operated by Sandia Corporation, a wholly owned subsidiary of Lockheed Martin Corporation, for the U.S. Department of Energy's National Nuclear Security Administration under contract DE-AC04-94AL85000.

# Sandia's History



exceptional service in the national interest.



# Sandia's Sites

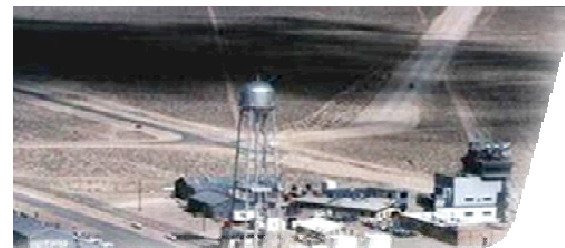
**Albuquerque,  
New Mexico**



**Livermore,  
California**



**Tonopah, Nevada**



**Waste Isolation Pilot Plant,  
Carlsbad, New Mexico**



**Pantex, Texas**



**Kauai, Hawaii**

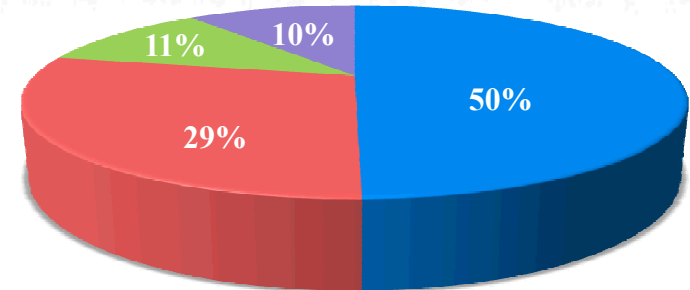




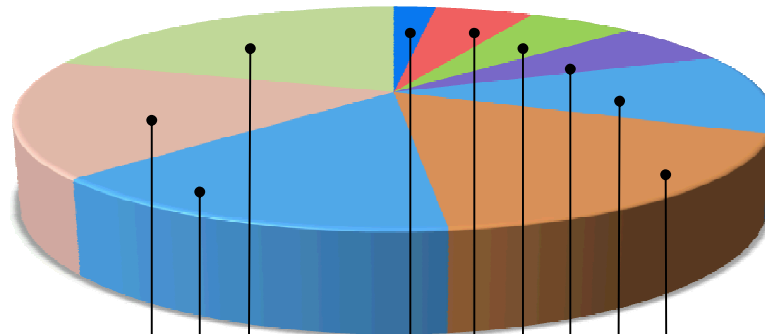
# People and Budget

- On-site workforce: 10,605
- Regular employees: 8,859
- Gross payroll: ~\$943 million

## FY11 Operating Revenue \$2.4 billion

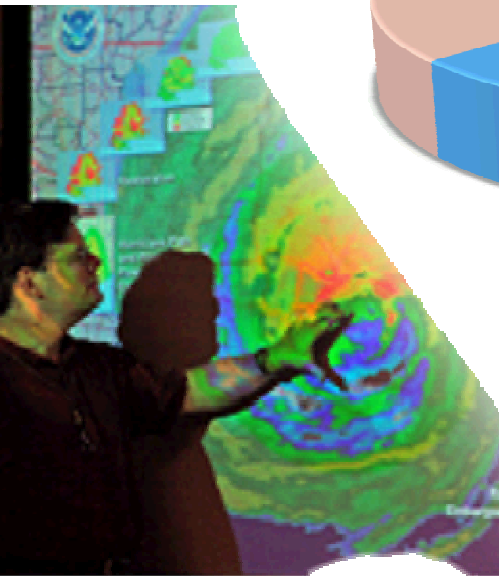


## Technical staff (4,344) by discipline

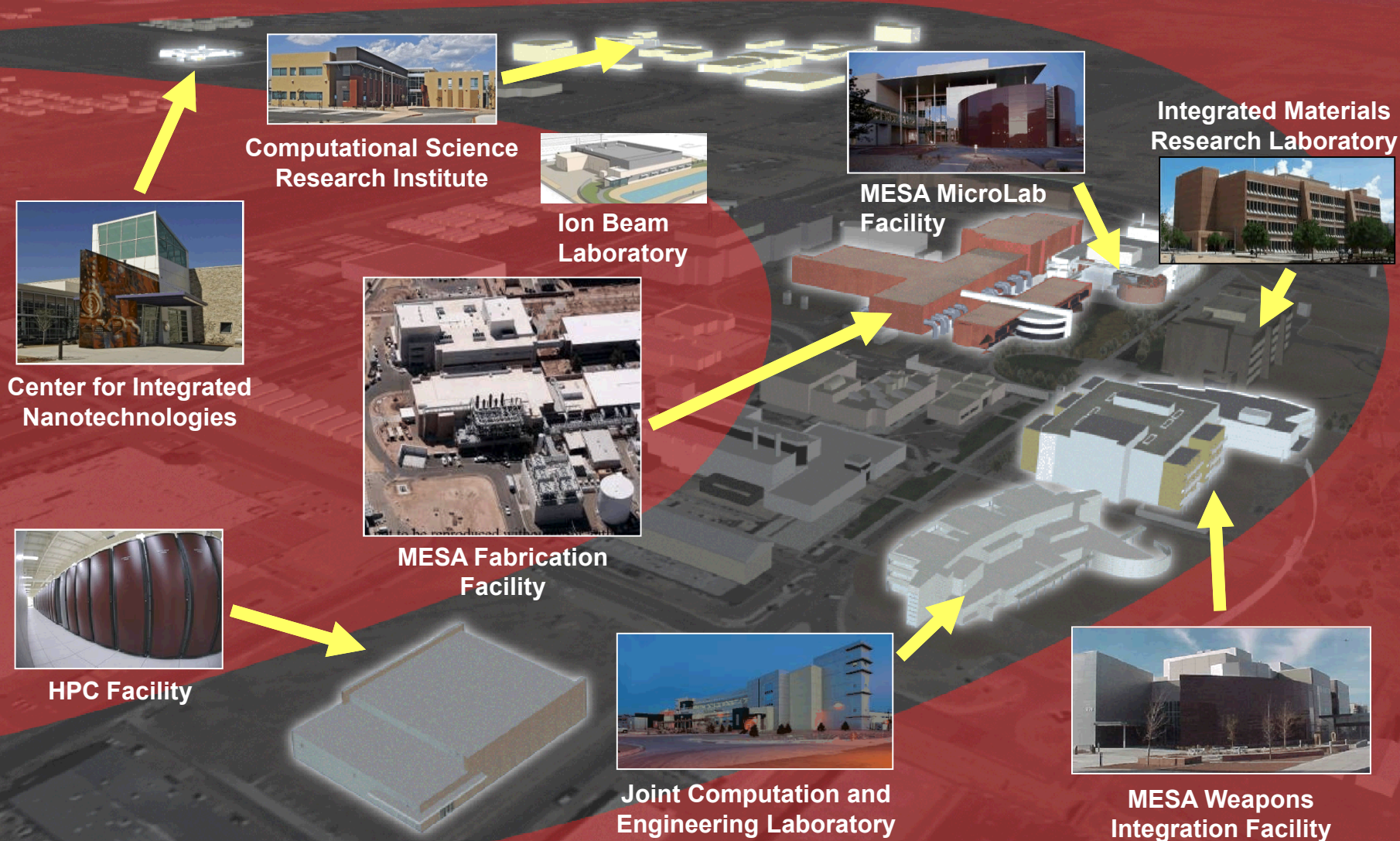


### (Operating Budget)

- Nuclear Weapons
- Defense Systems & Assessments
- Energy, Climate & Infrastructure Security
- International, Homeland, and Nuclear Security



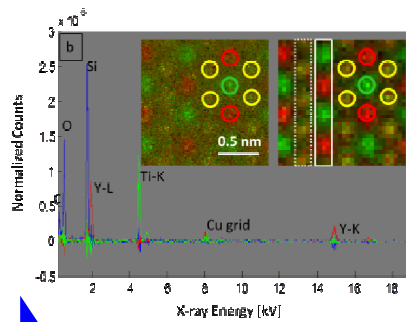
# Sandia's Innovation Corridor



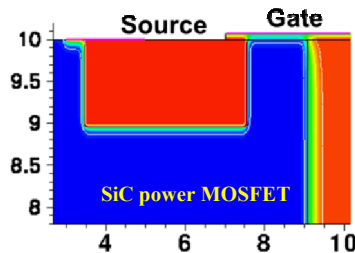


# SNL has Extensive R&D Capabilities in Wide Band Gaps – Materials, Devices, and Systems

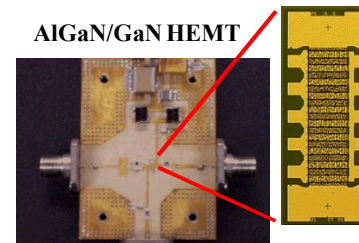
- 60+ years as DOE/NNSA mission lead in electronics
- 30+ years of compound semiconductor research
- 20+ years of wide band gap materials & device R&D
- **Facilities:** ~30,000 ft<sup>2</sup> clean room (MESA facility); Solid-State Lighting EFRC; microgrid testbed (DETL facility); ASIC design & fab; extensive reliability testing and failure analysis



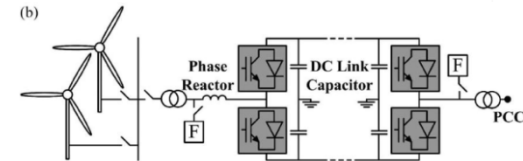
*Atomic-resolution characterization*



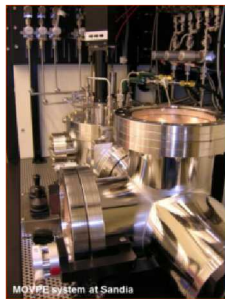
*Material and device simulation*



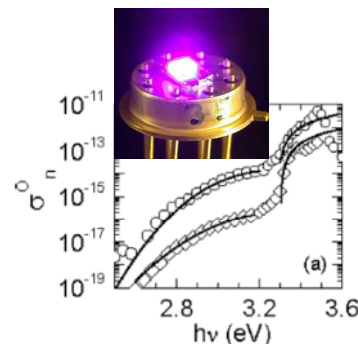
*Device fabrication (MESA fab)*



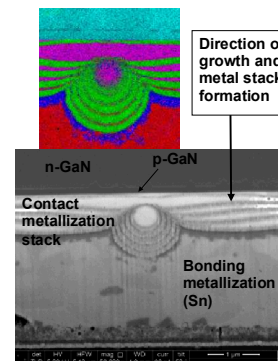
*Power circuits and systems*



*Epitaxial growth*



*Defect spectroscopy*



*Reliability physics*



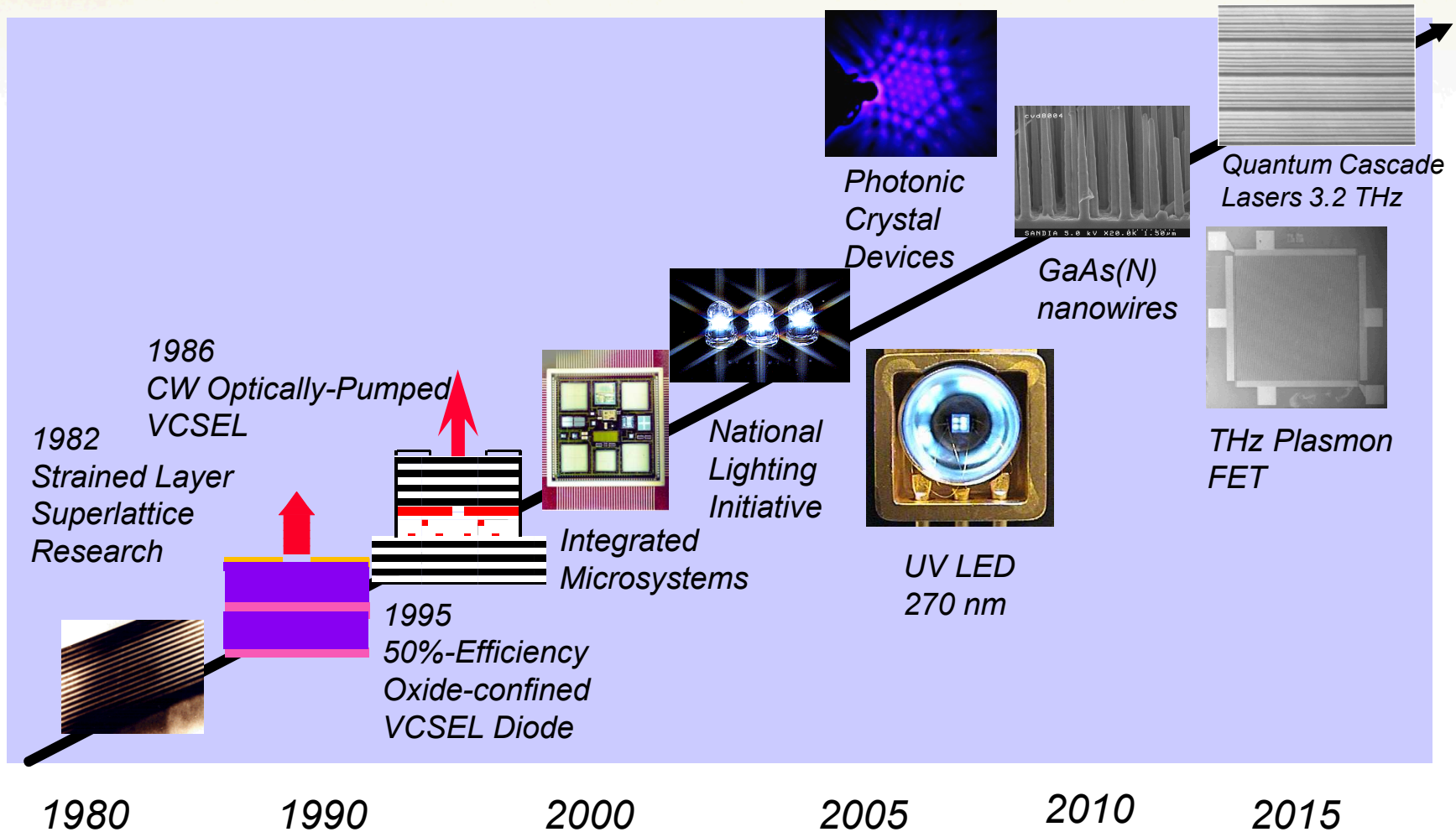
*Grid-level power networks (DETL)*

*Atomic scale*



*Grid scale*

# 1980-2012: 30+ years of Compound Semiconductor S&T



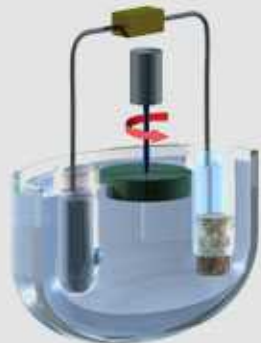
# WBG PE Under Sandia's Energy Storage Program

Funded by DOE Energy Storage Program (Dr. Imre Gyuk)  
Sandia's Energy Storage PE Program led by Dr. Stan Atcitty

## Materials R&D



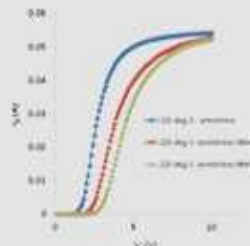
- Gate oxide R&D
- Bulk GaN



## Semiconductor devices



- Post-Si characterization & reliability
- SiC thyristors
- ETO



## Power Modules



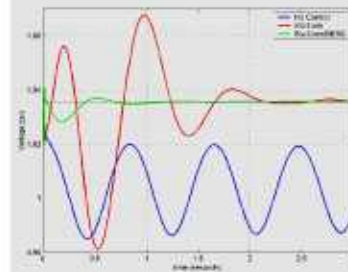
- High temp/density power module

## Power Conversion System



- DSTATCOM plus energy storage for wind energy
- Optically isolated MW inverter
- High density inverter with integrated thermal management
- High temp power inverter

## Applications



- Power smoothing and control for renewables
- FACTS and energy storage





# Comparison of Semiconductor Materials

**WBG materials allow higher photon energy for optoelectronics, and higher voltage, current, temperature, and frequency for power electronics**

Property	Si	4H-SiC	GaN	Diamond	AlN
Bandgap $E_g$ , (eV)	1.1	3.2	3.4	5.5	6.2
Dielectric constant, $\epsilon_r$	11.9	10.1	9	5.5	9
Electric breakdown field, $E_c$ (MV/cm)	0.3	2.2	3	10	13
Electron Mobility, $\mu_n$ (cm <sup>2</sup> /V·s)	1500	700	900 (bulk) 2000 (2D)	1900	300
Hole Mobility, $\mu_p$ (cm <sup>2</sup> /V·s)	600	115	150	600	20
Thermal Conductivity, $\lambda$ (W/cm·K)	1.5	4.9	> 1.3	22	2.9
Saturated Electron Drift Velocity, $v_{sat}$ ( $\times 10^7$ cm/s)	1	2	2.5	2.7	1.2



# WBGs Are Increasingly Critical to Energy Technologies

Transitioning to cleaner and more efficient energy sources will require development and integration of WBG devices

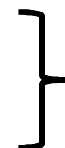


Power electronics and inverters for electric vehicles and the electrical grid



Solid-state lighting

Material	Bandgap (eV)
Si	1.1
4H-SiC	3.2
GaN	3.4
Diamond	5.5
AlN	6.2



Wide-Bandgap



Ultra-Wide-Bandgap



# WBGs Enable Reductions in Power Loss, Size, and Weight

Device	Brkdwn Voltage	$P_{\text{switching}}$ 500 Hz	$P_{\text{switching}}$ 5 kHz	$P_{\text{switching}}$ 20 kHz	$P_{\text{conduction}}$ 100°C
Cree SiC MOSFET	12 kV	4 W/cm <sup>2</sup>	40 W/cm <sup>2</sup>	160 W/cm <sup>2</sup>	100 W/cm <sup>2</sup>
ABB Si IGBT	2x6.5 kV	72.5 W/cm <sup>2</sup>	725 W/cm <sup>2</sup>	2900 W/cm <sup>2</sup>	182 W/cm <sup>2</sup>

**Cree/Powerex/GE**

**Si IGBT module  
13.5 kV, 100 A**

**SiC MOSFET  
module  
10 kV, 120 A**

SiC MOSFET  
module is 10%  
weight and 12%  
volume of Si  
IGBT module



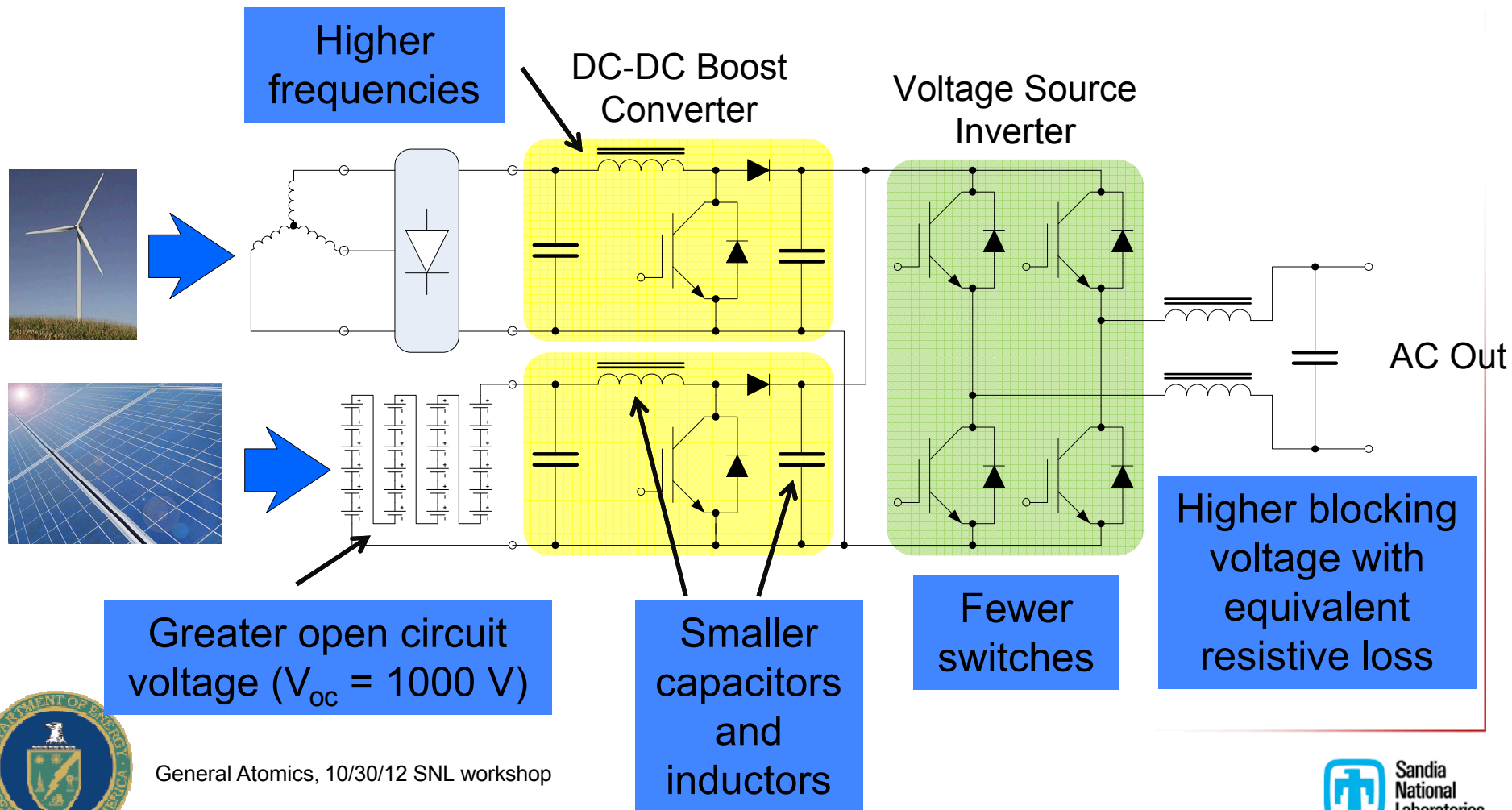
M. K. Das et al., ICSCRM 2011





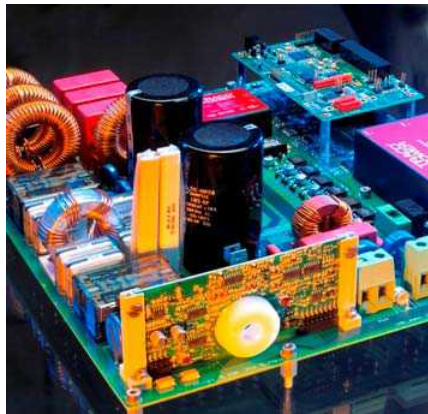
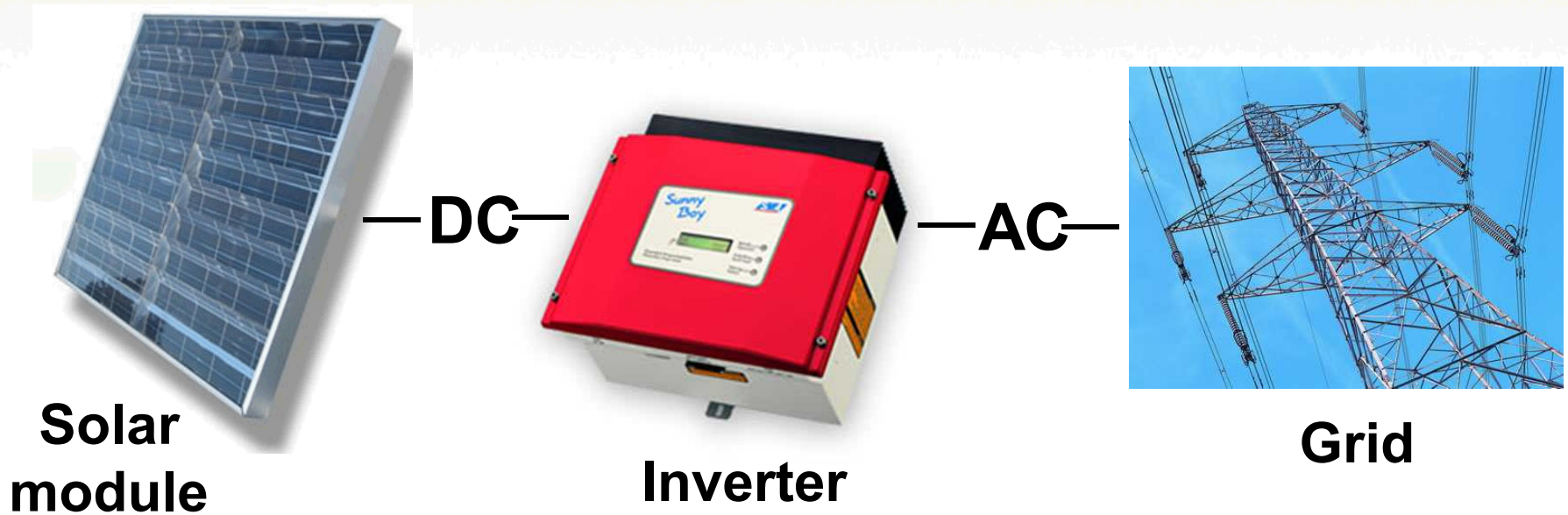
# WBGs for Increased Grid Efficiency and Resiliency

A modern, resilient electric grid with integrated renewable power sources requires power electronics and power inverters



General Atomics, 10/30/12 SNL workshop

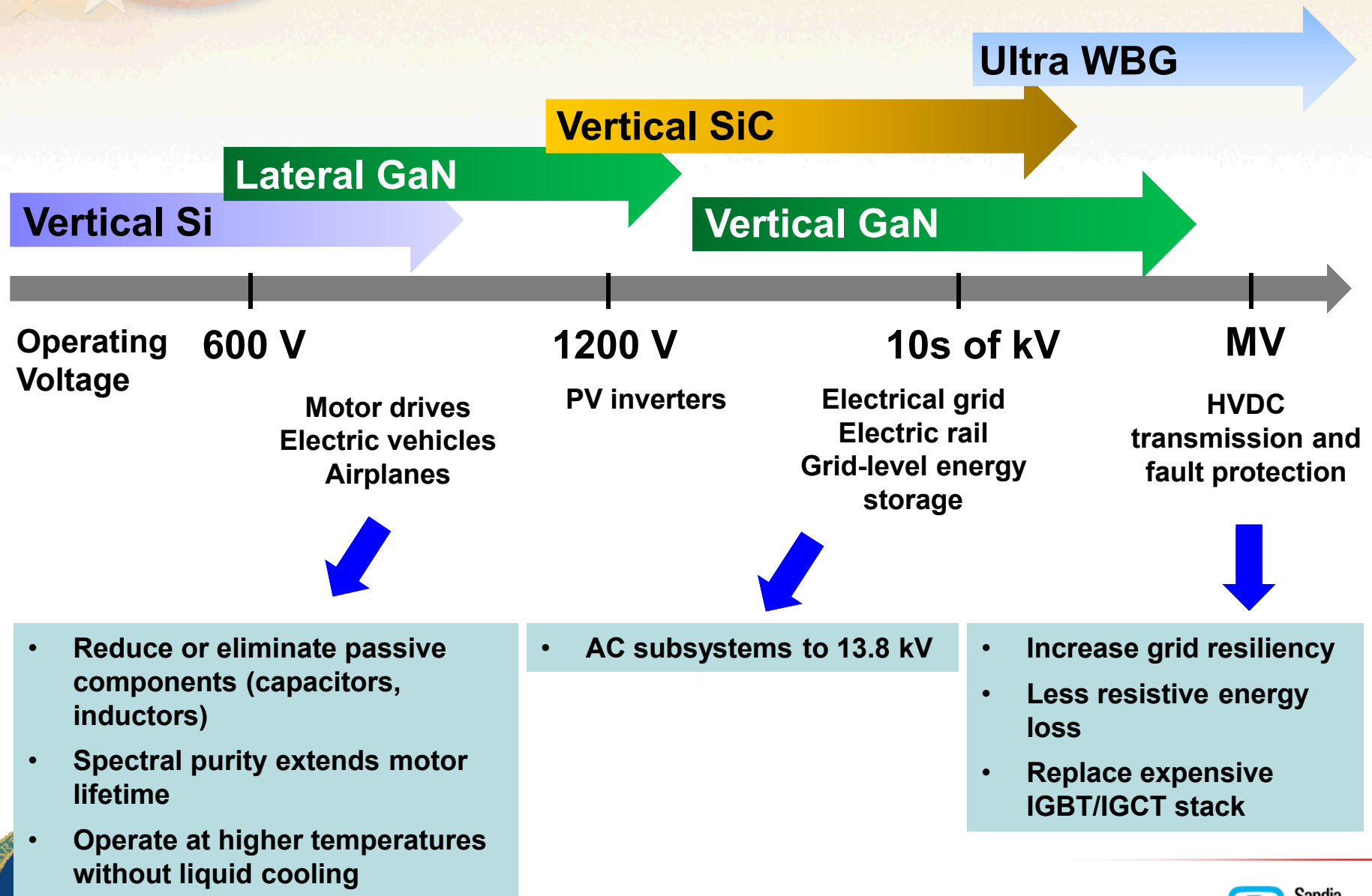
# WBG Power Devices for PV Inverters



Circuit board from Fraunhofer  
97.5% efficient PV inverter  
using SiC MOSFETs



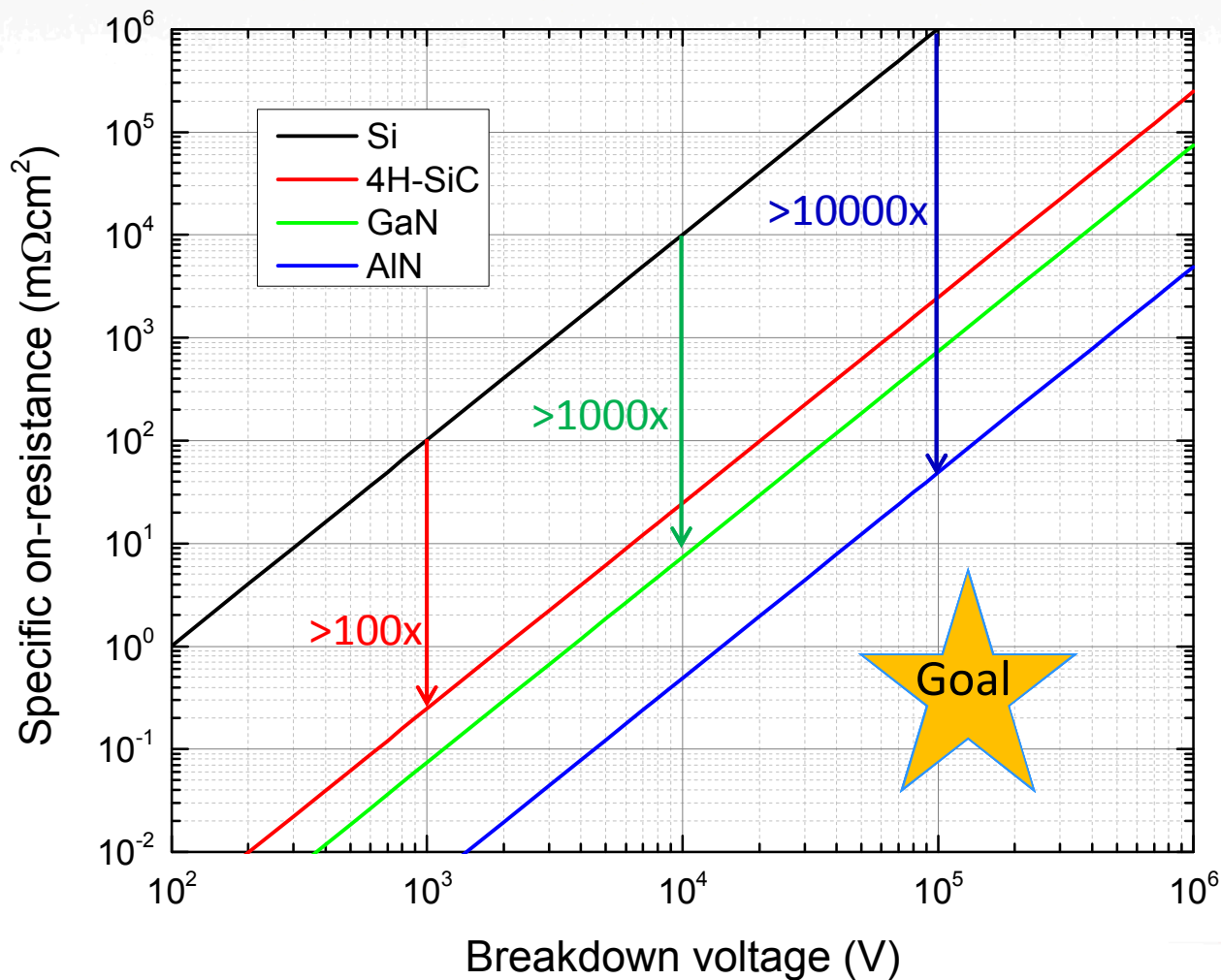
# Application Space for WBG Devices



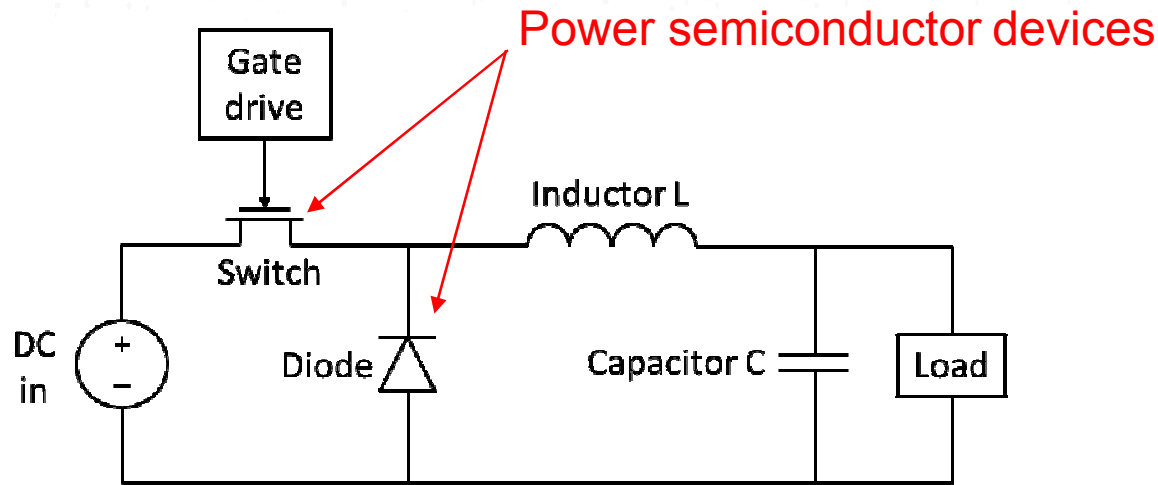


# WBGs Offer Orders-of-Magnitude Improvement for PE

Unipolar Figure-of-Merit for Various Materials

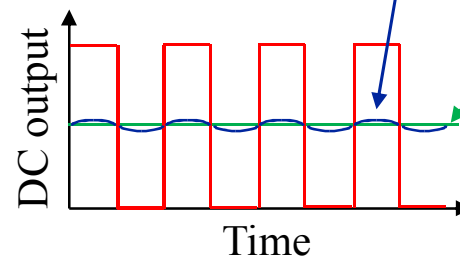
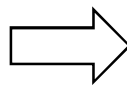
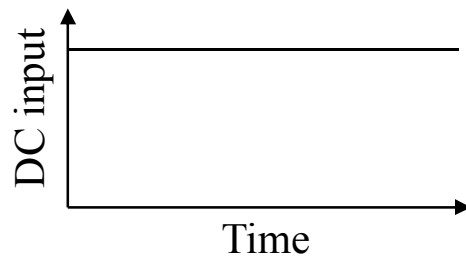


# Example Power Electronics Circuit: Step-Down (Buck) DC-to-DC Converter

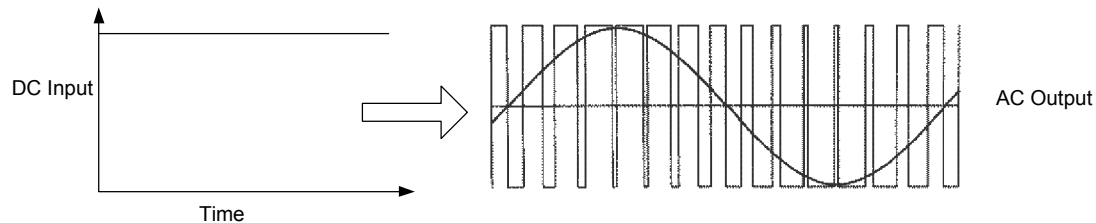
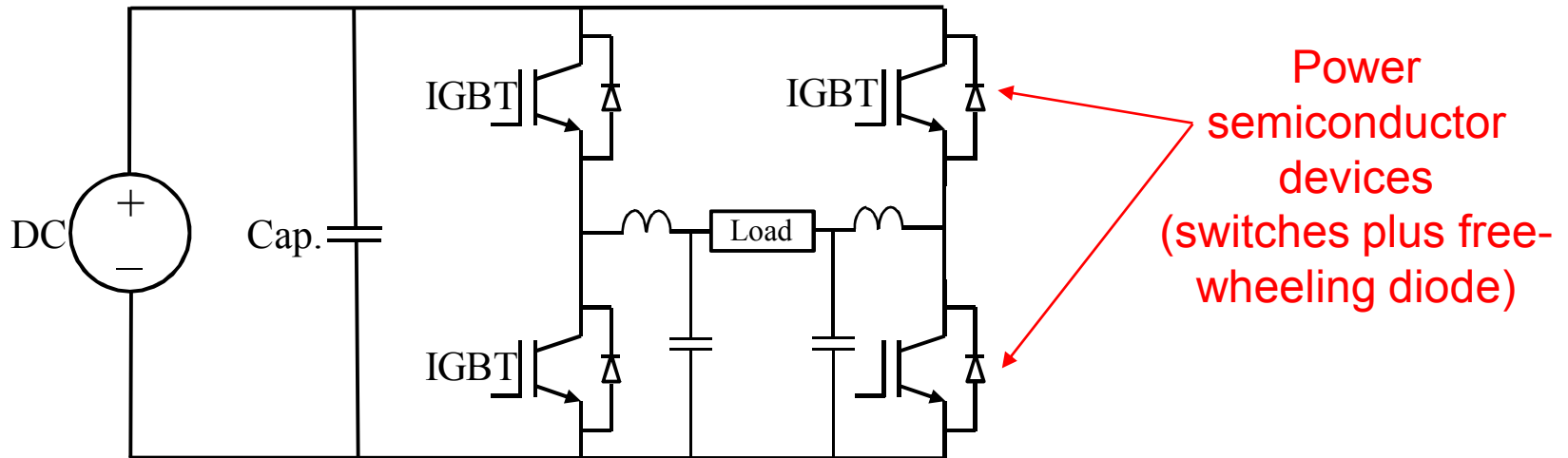


$$\frac{V_{\text{ripple}}}{V_{\text{out}}} = \frac{1 - D}{8LCf^2}$$

PWM (e.g. 100 kHz)  
Duty cycle = D  
 $V_{\text{out}} = DV_{\text{in}}$



# Example of Power Electronics Circuit: Single-Phase Inverter

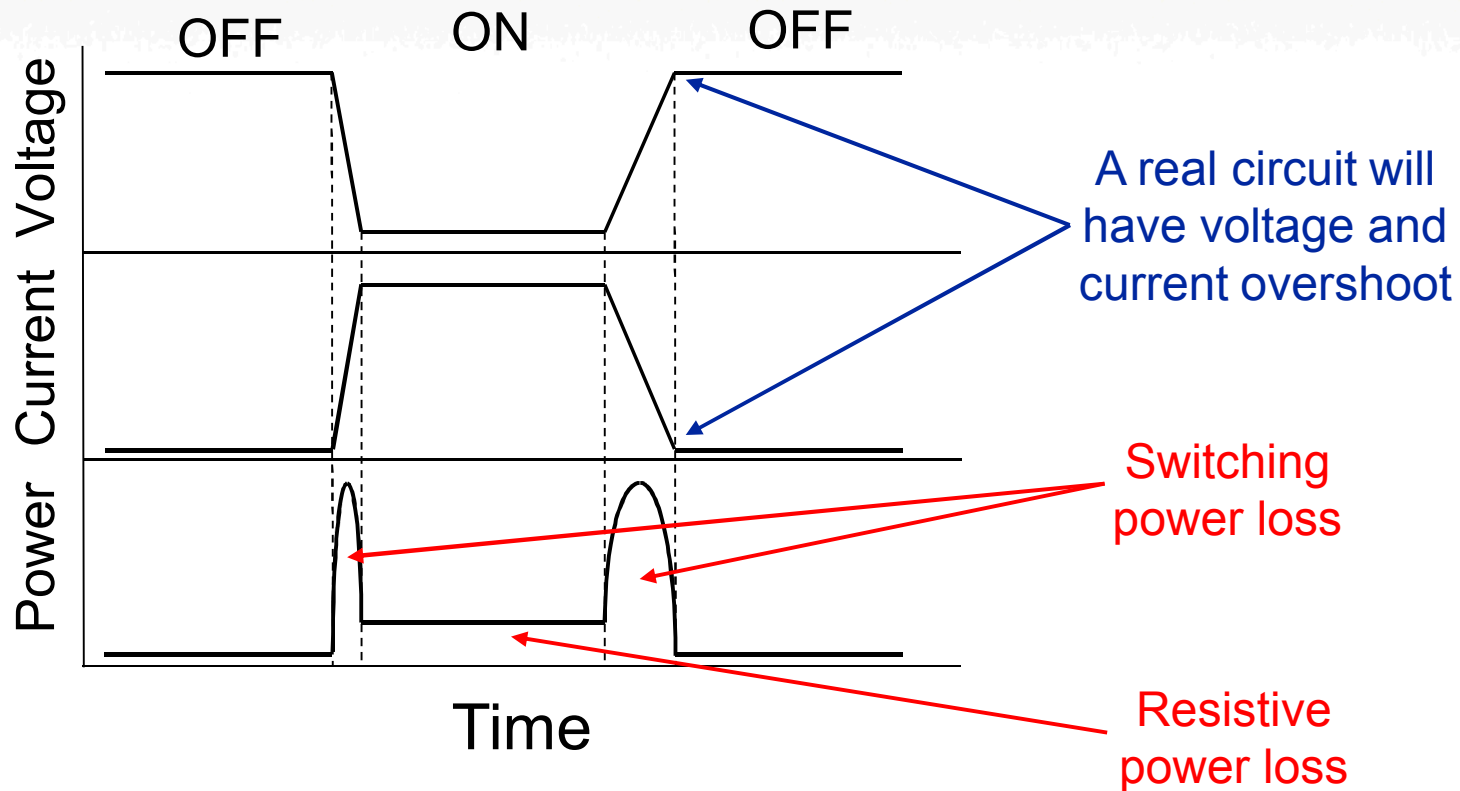


Pulse-Width Modulation (PWM) 10 – 20 kHz





# PE Switch Current, Voltage, and Power Waveforms



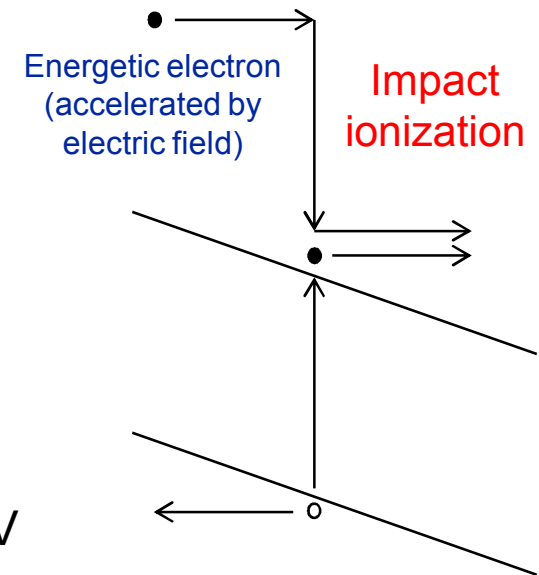
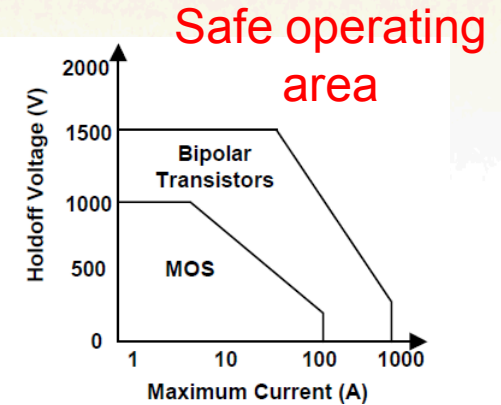
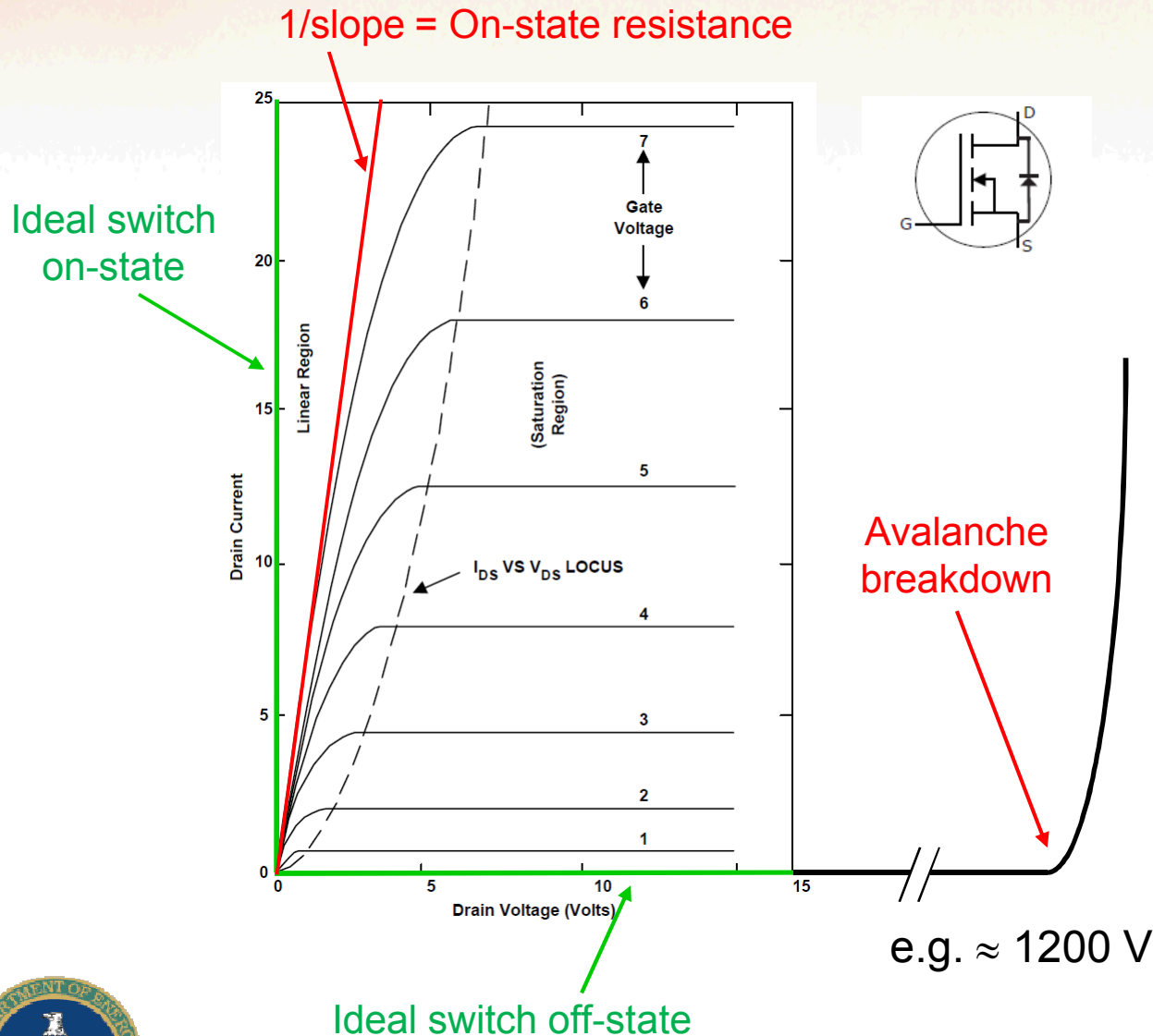
Minimum ON-state loss: Low  $R_{on}$

Minimum OFF-state loss: Low leakage

Minimum switching loss: Fast switching transients

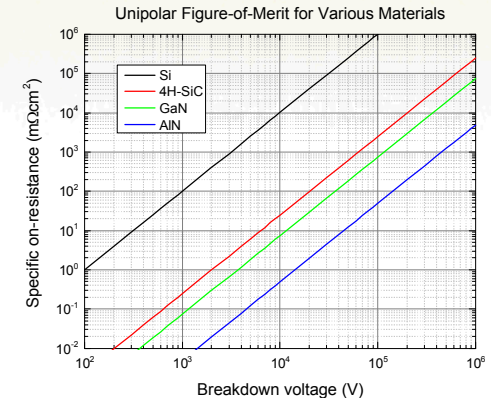
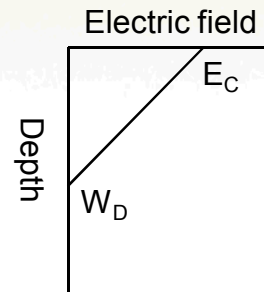
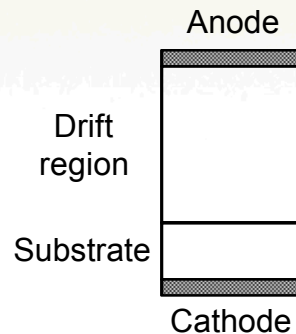
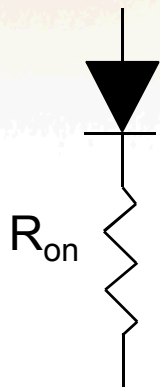


# Real Power Devices are NOT Ideal Switches!



Figures from International Rectifier "Power MOSFET Basics" pamphlet

# Unipolar Power Device Figure-of-Merit

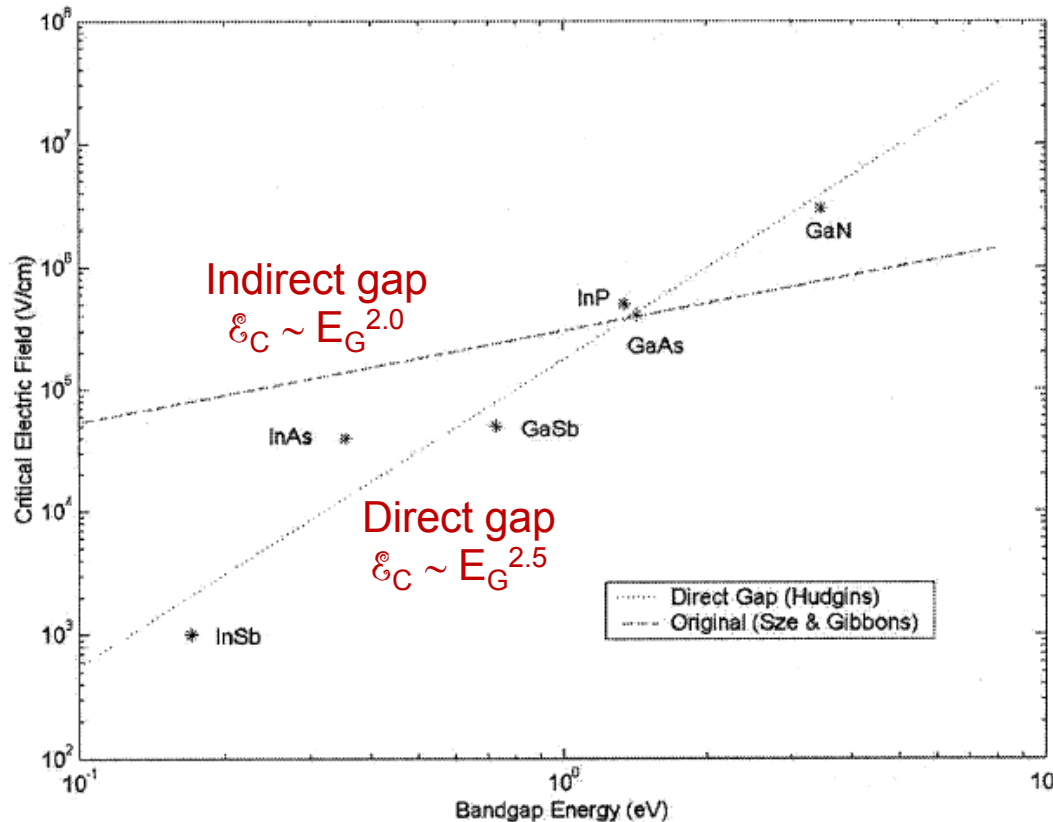


- Off-state: Integrate electric field to get breakdown voltage  $V_B = W_D E_C / 2$  (1)
- Gauss' law:  $\epsilon E_C = q N_D W_D$  (2)
- On-state: Current transport due to carrier drift, resistance  $R_{on} = W_D / \sigma A$   
 Conductivity  $\sigma = q \mu_n n = q \mu_n N_D$  assuming complete dopant ionization  
 Specific on-resistance  $R_{on,sp} = R_{on} A = W_D / \sigma = W_D / q \mu_n N_D$  (3)
- Combining (1) and (2) gives dependence of  $V_B$  on  $N_D$  and  $E_C$ :  $V_B = \epsilon E_C^2 / 2 q N_D$
- Combining (1), (2), and (3) one obtains the unipolar “figure-of-merit”:  
 $R_{on,sp} = 4 V_B^2 / \epsilon \mu_n E_C^3 \rightarrow V_B^2 / R_{on,sp} = \epsilon \mu_n E_C^3 / 4$





# Dependence of Critical Electric Field on Bandgap



Thus, a very strong dependence of FOM on  $E_G$ !

- Direct: FOM  $\sim E_G^{7.5}$
- Indirect: FOM  $\sim E_G^{6.0}$



J. L. Hudgins, G. S. Simin, E. Santi, and M. A. Khan, "An Assessment of Wide Bandgap Semiconductors for Power Devices," IEEE Trans. on Elect. Dev. **18(3)**, 907 (2003).

# Application Classes of Power Devices

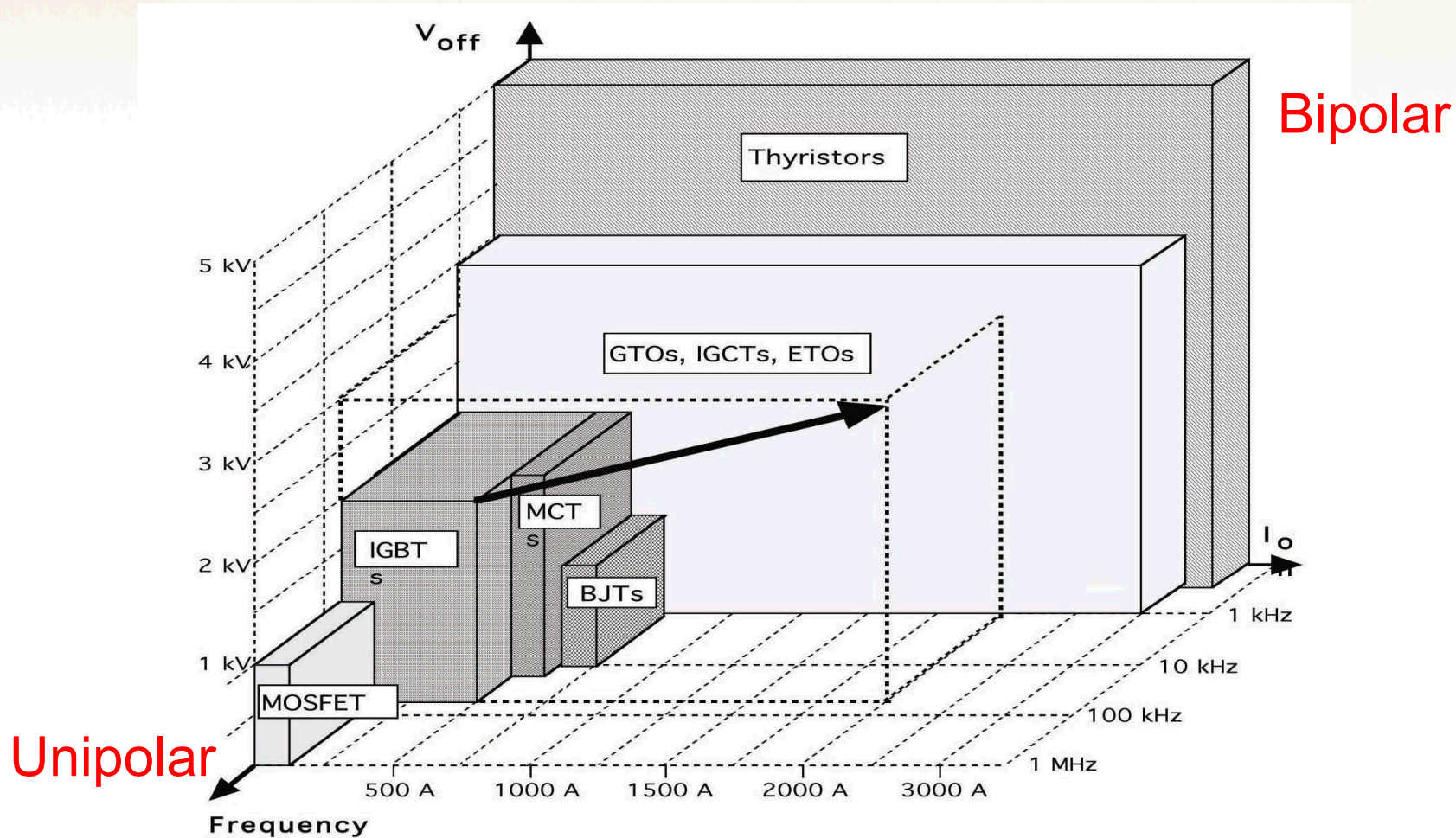
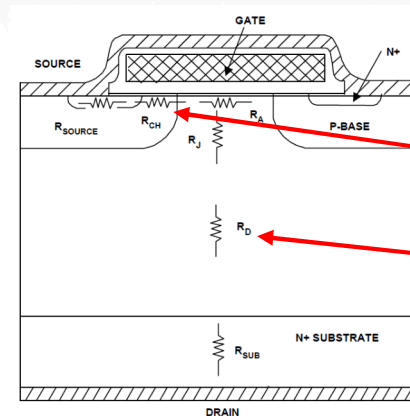
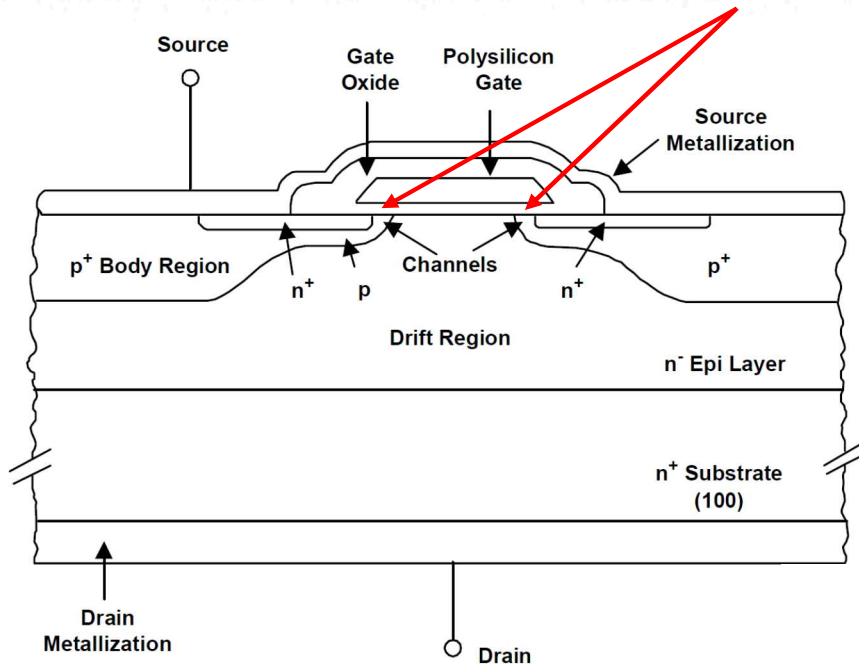


Figure from Mohan et al., "Power electronics: Converters, Applications, and Design" (Wiley, 2003).



# SiC Power D-MOSFET

Critical gate oxide  
interfacial region



Channel resistance  
can dominate  
drift region  
resistance

Charge injection due to  
small band offset at  
SiO<sub>2</sub>/SiC interface  
enhances  $V_T$  shift

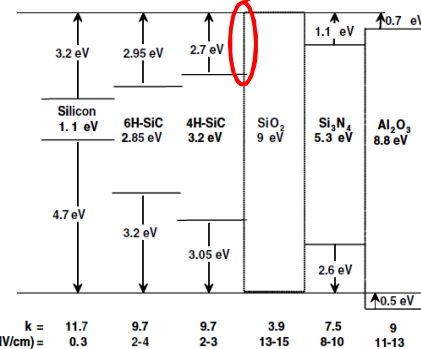


Fig. 1. Dielectric constants, and critical electric fields of various semiconductors (Si, 6H-SiC, 4H-SiC) and dielectrics (SiO<sub>2</sub>, Si<sub>3</sub>N<sub>4</sub> and Al<sub>2</sub>O<sub>3</sub>). Conduction and valence band offsets of these are also shown with respect to SiO<sub>2</sub>.

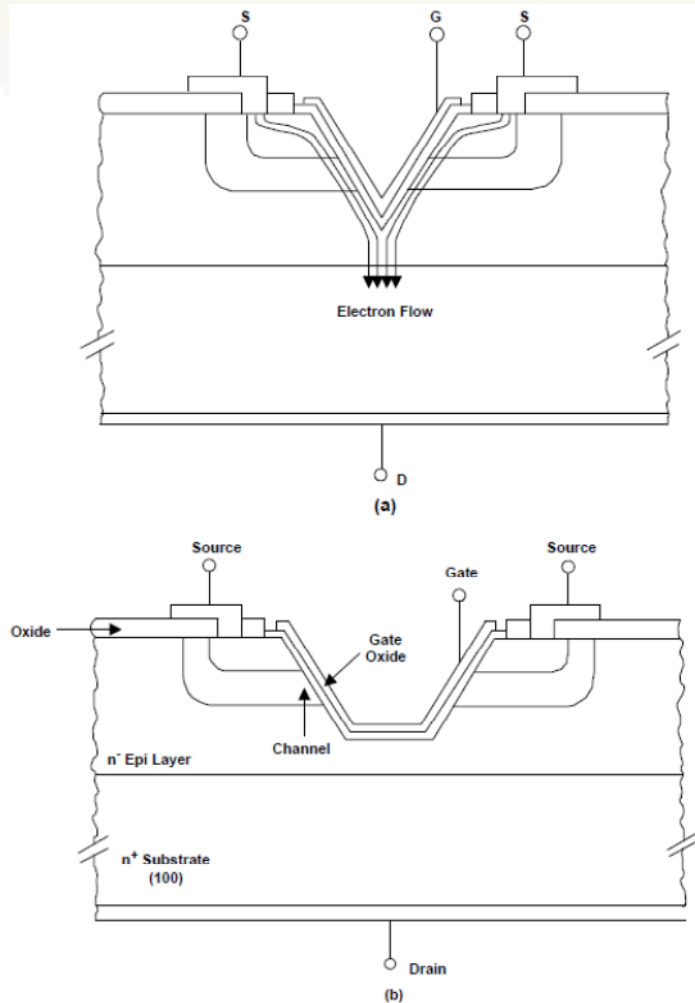
R. Singh, Microelectronics Reliability, v. 46, p. 713 (2006).

Figures from International Rectifier "Power MOSFET Basics" pamphlet





# SiC V- and U-MOSFETs



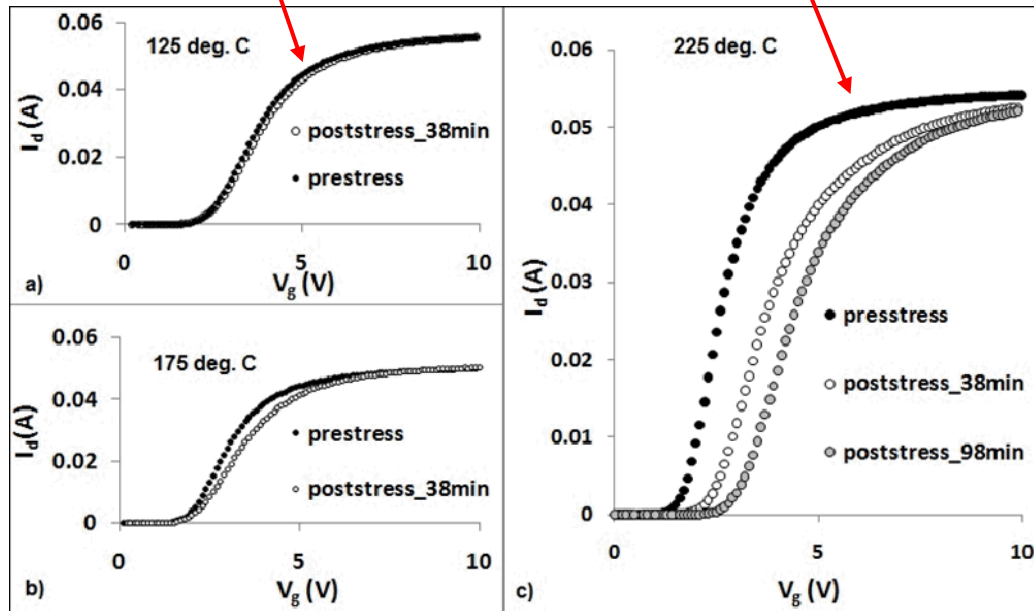
- No double implant
- Channel forms along different crystal plane (generally higher  $D_{IT}$  and lower  $\mu$ )
- Potentially high electric fields at bottom corners
- Earliest SiC power MOSFETs were of this type (or with vertical sidewalls)



# SiC MOSFET Gate Voltage Stress at High T

Minimal degradation  
at rated temp.

Severe degradation  
at high temp.

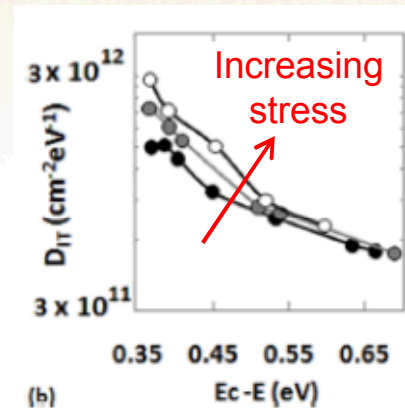


Stress:  $V_{GS} = +20$  V,  $V_{DS} = 0.1$  V

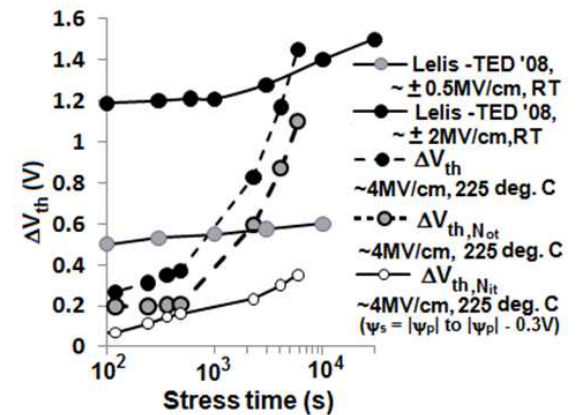


TO-247-3

Commercial 1200 V  
SiC MOSFET



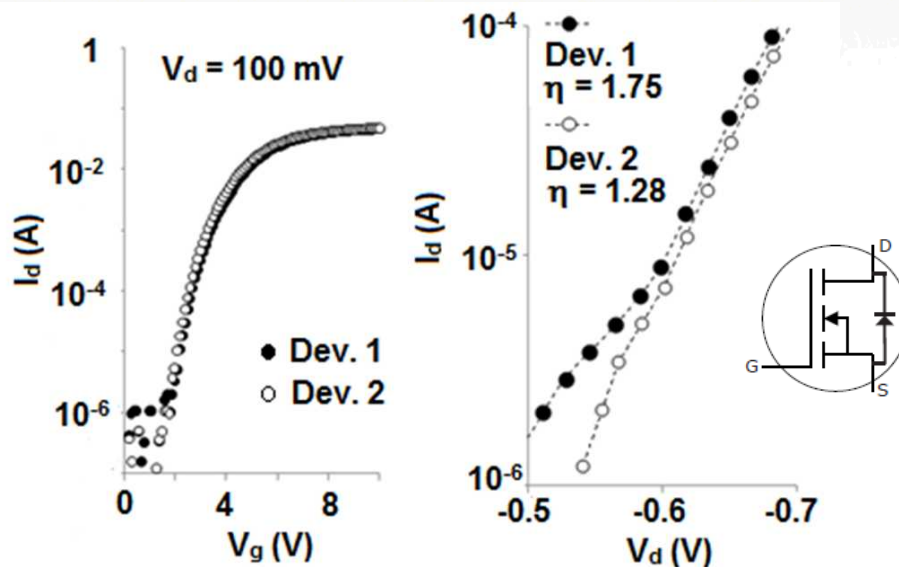
Interface state density



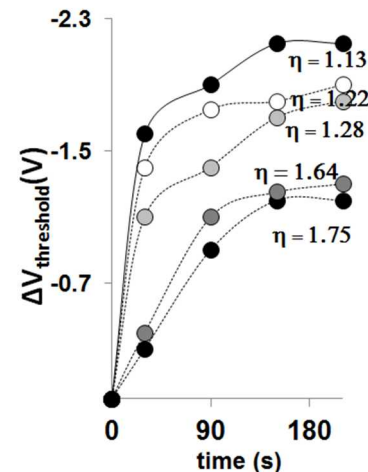
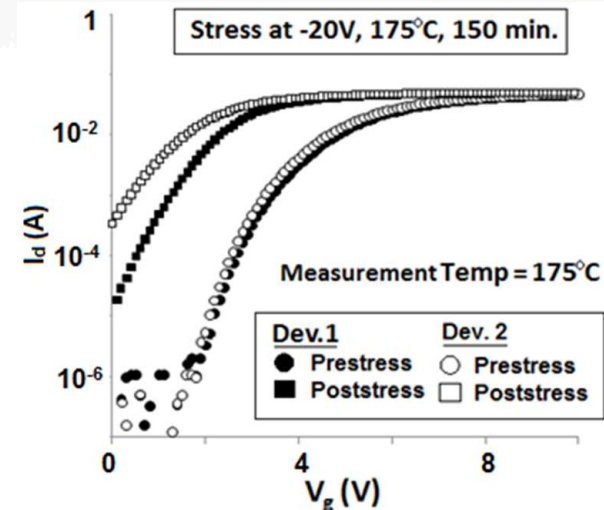
Evolution of interface  
and bulk trapping  
components vs. time



# Integrated Free-Wheeling Diode Characteristics and Hole Trapping



SiC MOSFETs with nearly identical  $I_D$ - $V_{GS}$  curves show differences in free-wheeling diode ideality factor; higher  $\eta$  devices show more hole trapping for given stress condition





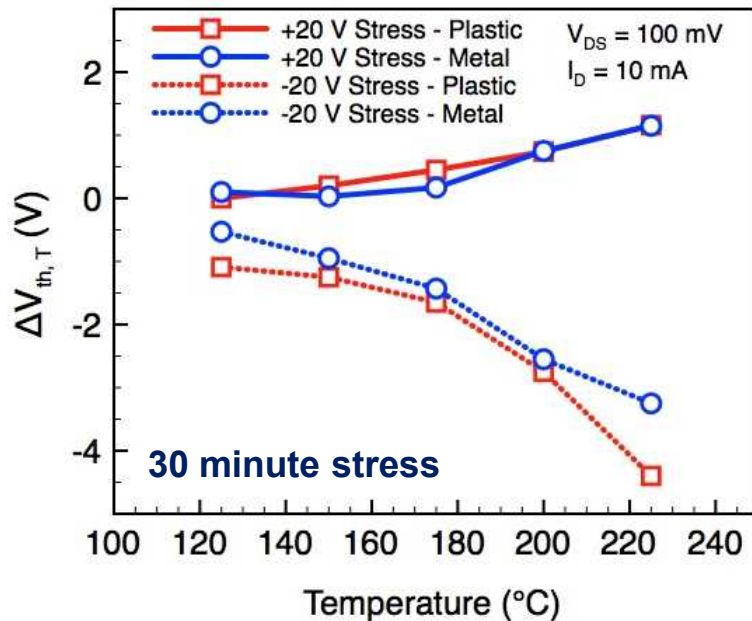
# SiC Power MOSFET Threshold Voltage Instability



Plastic



Metal



**Threshold voltage shift  
is independent of  
packaging type**

- Shift in threshold voltage  $\Delta V_T$  (likely due to charge trapping in the gate oxide) will change  $R_{ON}$  and thus the ON-state conduction power loss

- $\Delta V_T$  is a function of time  $t$ , gate voltage  $V_G$ , and temperature  $T$

- Assume a power-law dependence on  $t$  and  $V_G$ , and an Arrhenius dependence on  $T$

- For *positive*  $V_G$ :

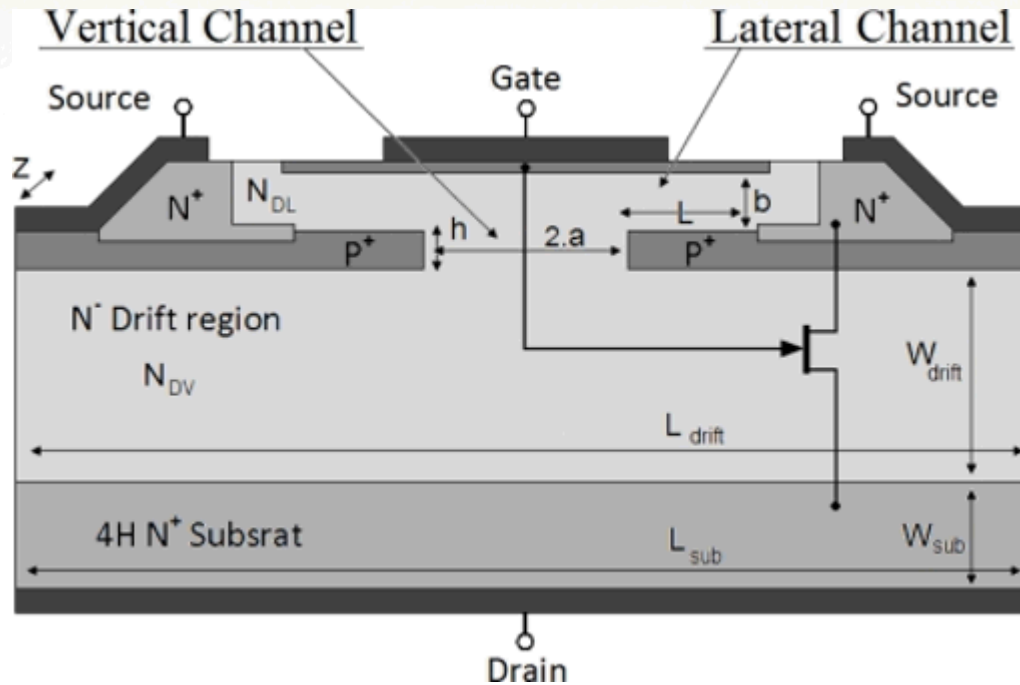
$$\Delta V_T = 8.5 \times 10^{-3} t^{0.40} V_G^{3.8} \exp(-0.34/kT)$$

- For *negative*  $V_G$ :

$$\Delta V_T = -1.4 \times 10^{-2} t^{0.42} |V_G|^{0.79} \exp(-0.33/kT)$$



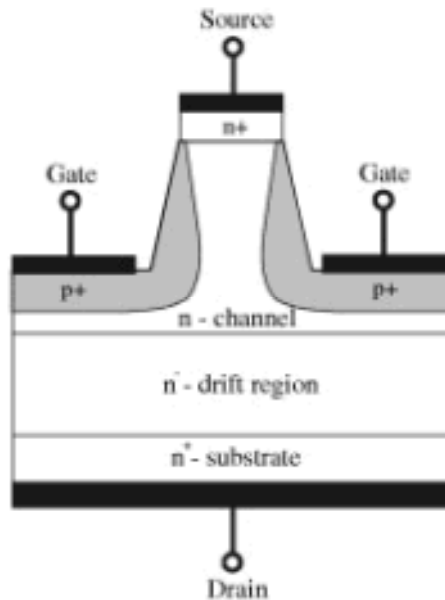
# SiC Junction FET



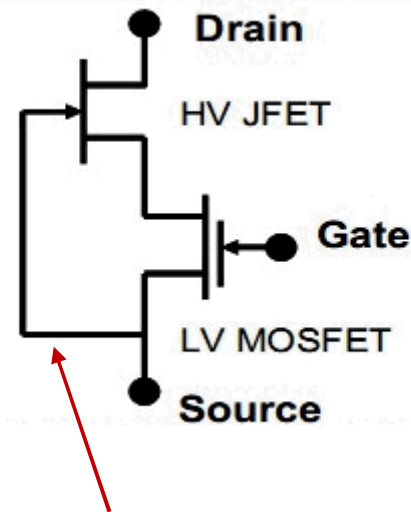
- No gate oxide, so fewer high-temperature reliability concerns
- MOST JFETs are normally-on, which is undesirable for circuits
- Normally-off JFETs suffer from high gate current (fwd. pn junction)



# Cascode Configuration for Normally-Off Operation



High-voltage,  
normally-on JFET



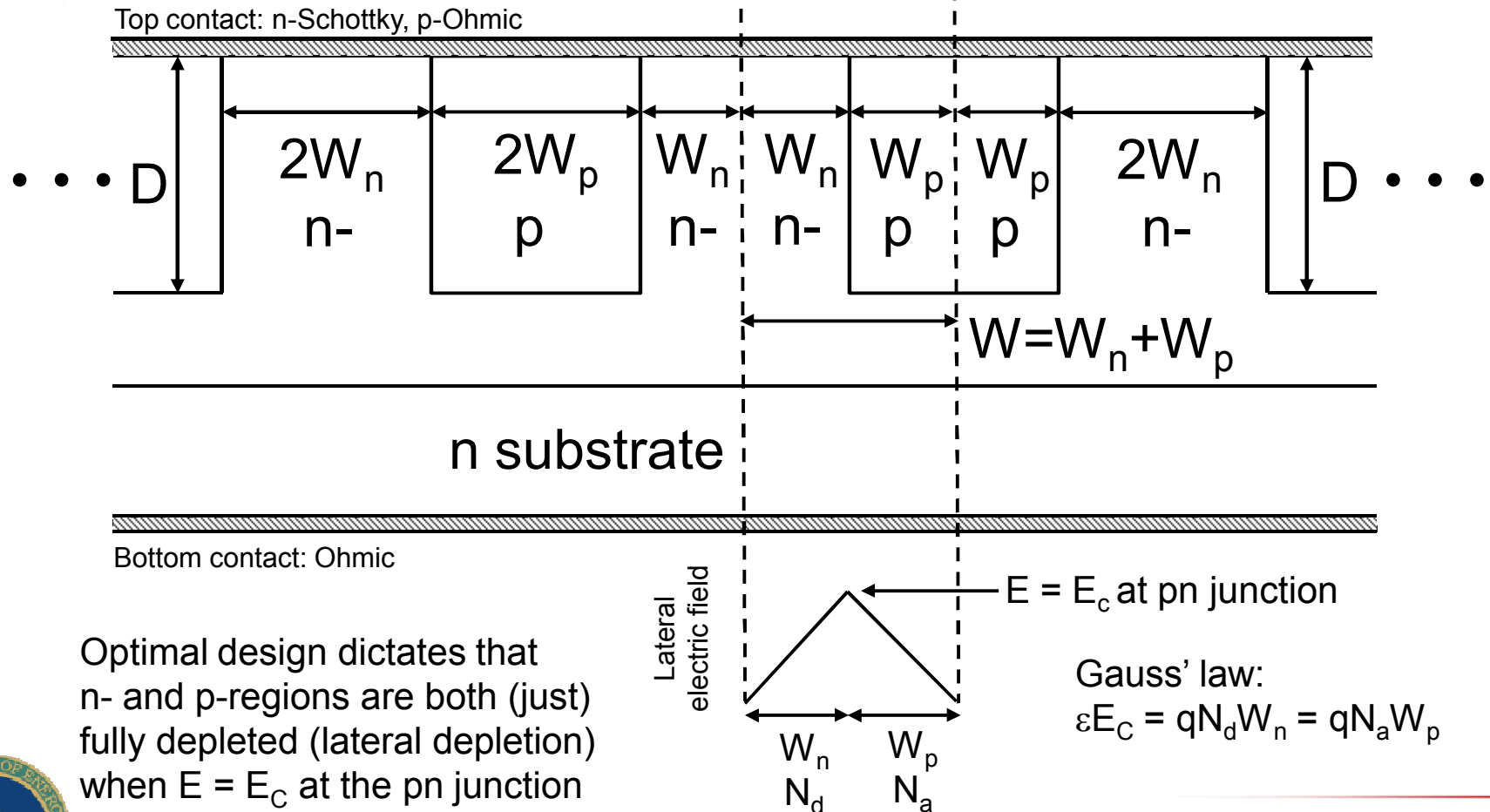
Gate voltage for the HV  
normally-on device equals  
negative of the drain voltage  
of the LV normally-off device;  
**combination acts as a  
normally-off HV switch**



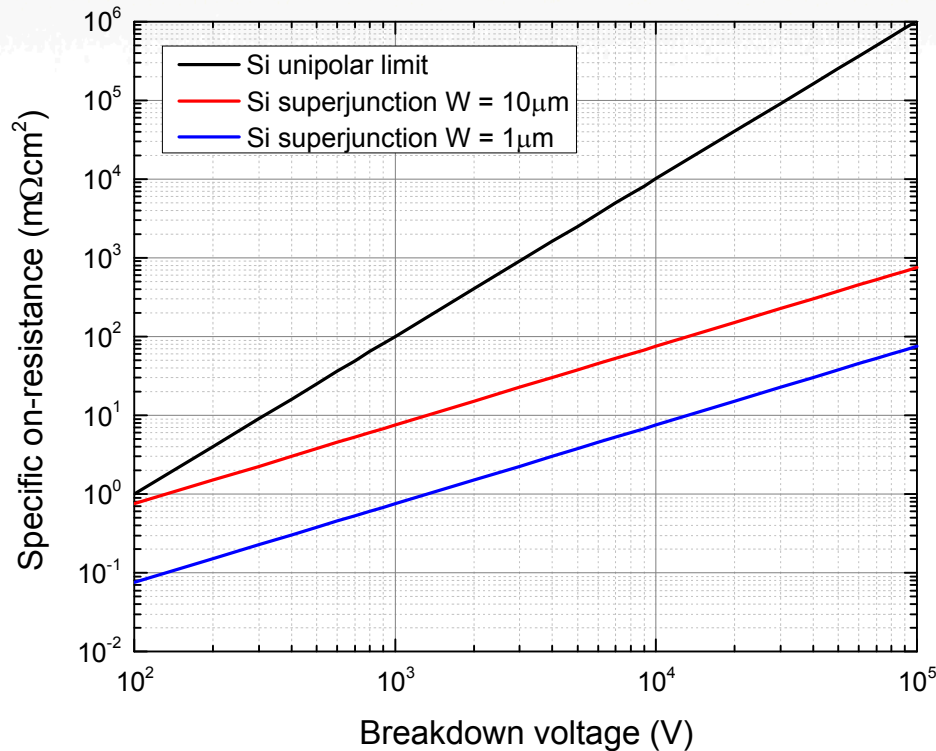


# Charge Coupled “Superjunction” for Improved $R_{ON}$ vs. $V_{BD}$

Vertical dashed lines indicate boundaries of one “cell”



# Superjunction can Surpass Unipolar “Limit”



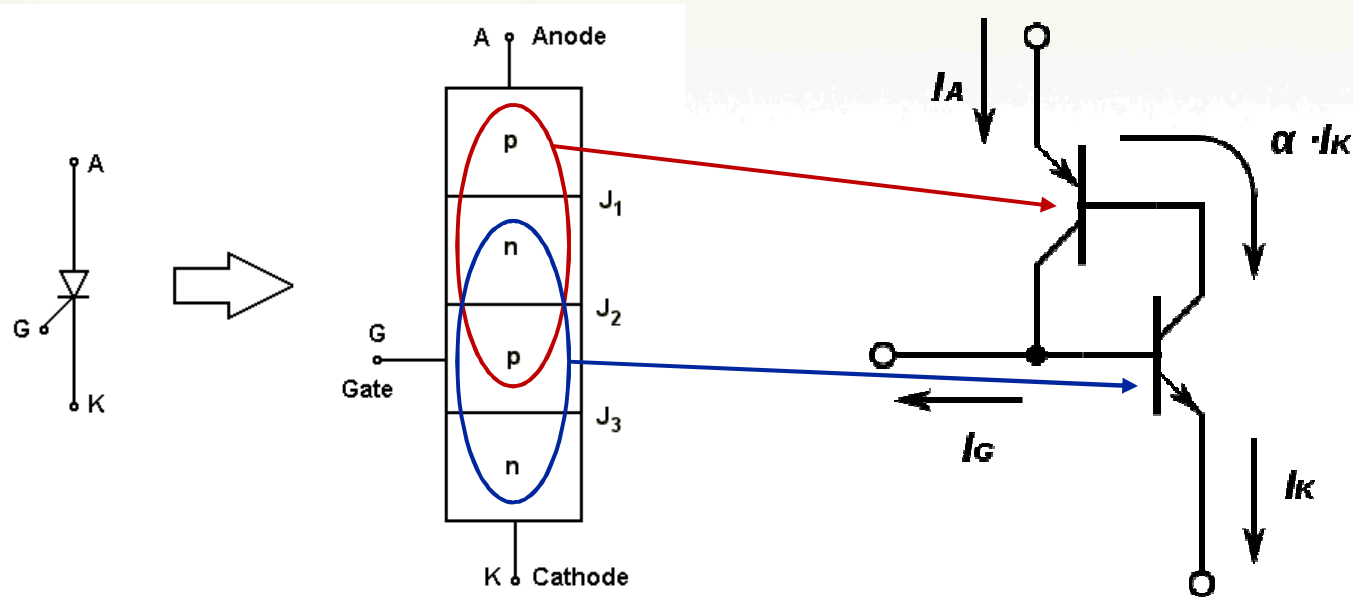
$$R_{sp,on} = \frac{WV_b}{m_n \epsilon E_C^2}$$

Note that  $R_{sp,on}$  is  
*linear* in  $V_B$  and  
*quadratic* in  $E_C$

By designing the device appropriately (small  $W$ ), it is possible to get lower  $R_{on,sp}$  for a given breakdown voltage (i.e. to surpass the unipolar “limit”)



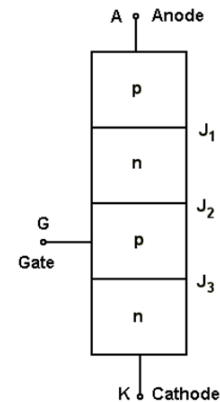
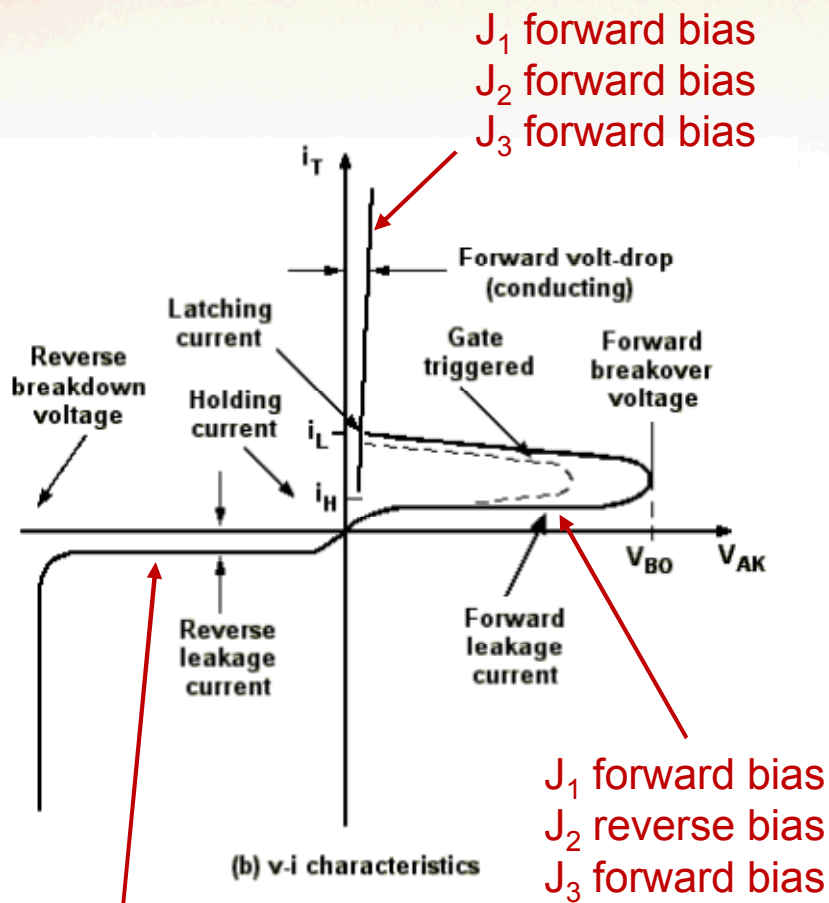
# Bipolar Device: Thyristor



- Three-junction device
- Can be modeled as two coupled bipolar transistors
- Turns on when sum of collector-to-emitter gains approaches 1



# Thyristor IV Characteristics

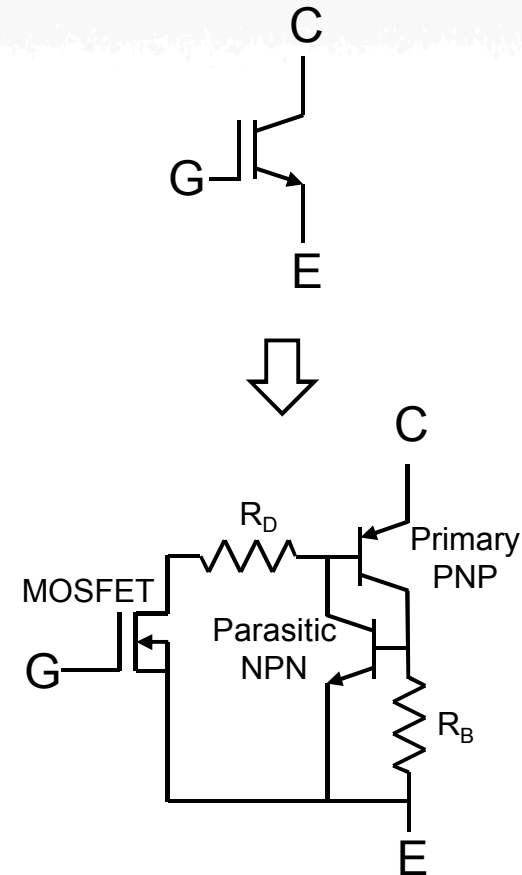
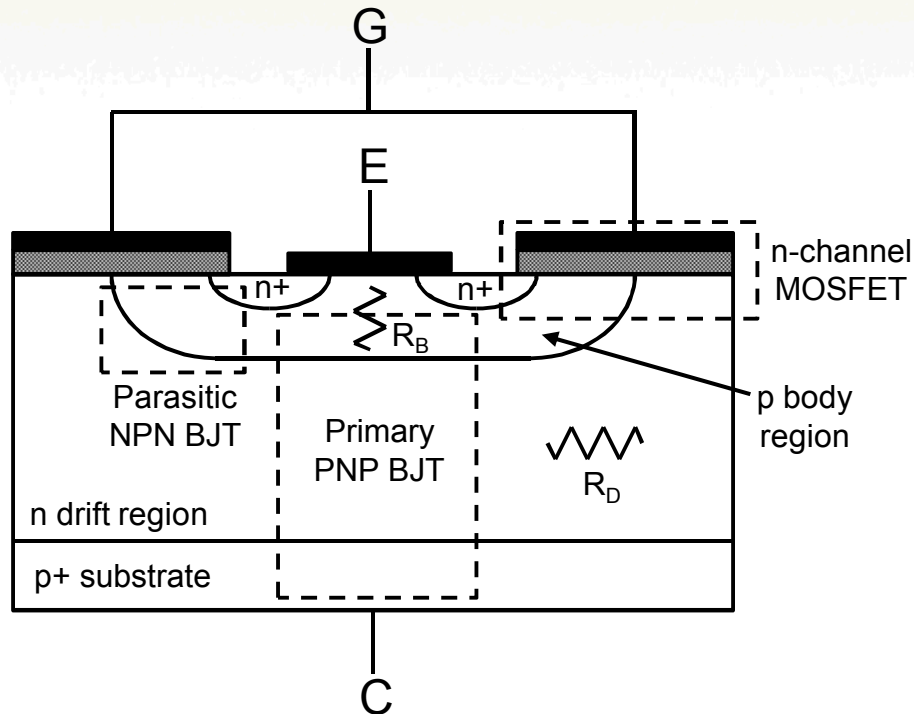


- Gate is used to inject carriers to switch from forward blocking to reverse blocking
- Difficult to turn off (quasi-controlled “gate turn-off” devices do exist)
- Slow switching due to minority-carrier recombination





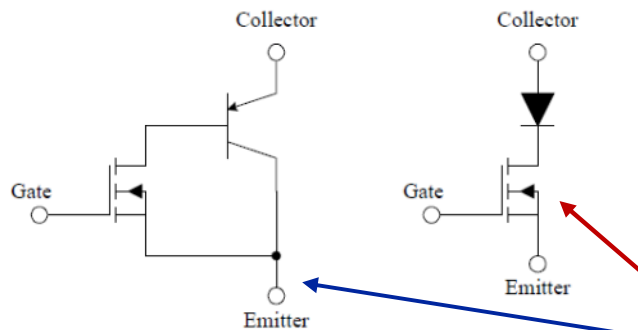
# Insulated-Gate Bipolar Transistor (IGBT)



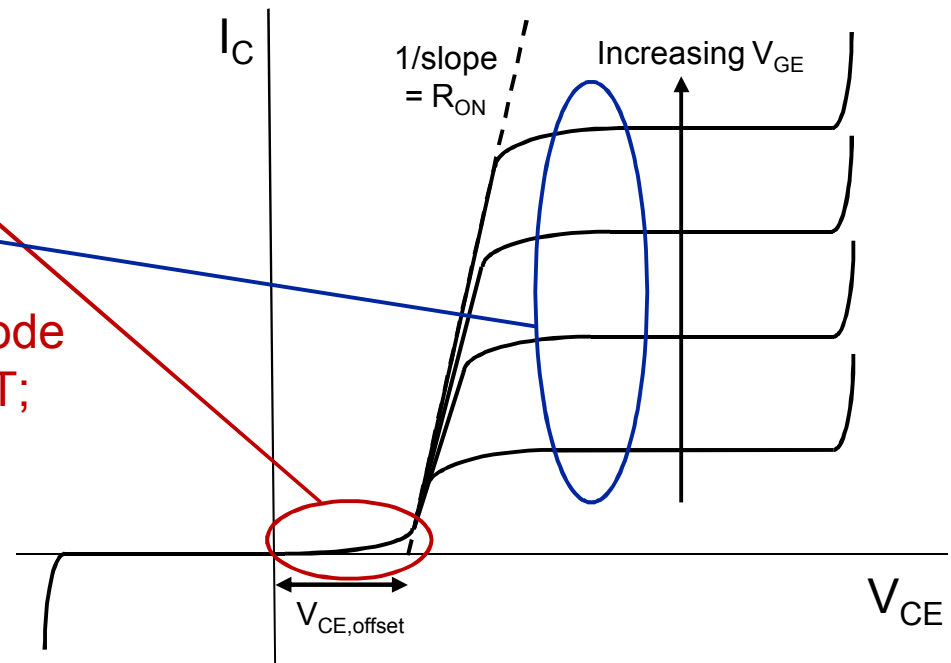
- Hybrid MOS-bipolar device
- Drain current of the MOSFET is the base current of the BJT
- High voltage and current capability with advantage of gate control
- Relatively slow switching



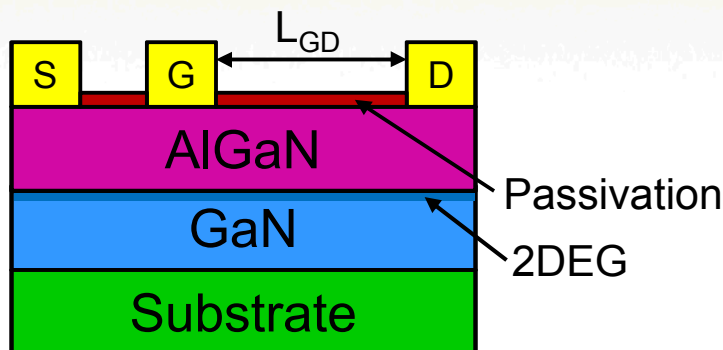
# IGBT IV Curves and Equivalent Circuits



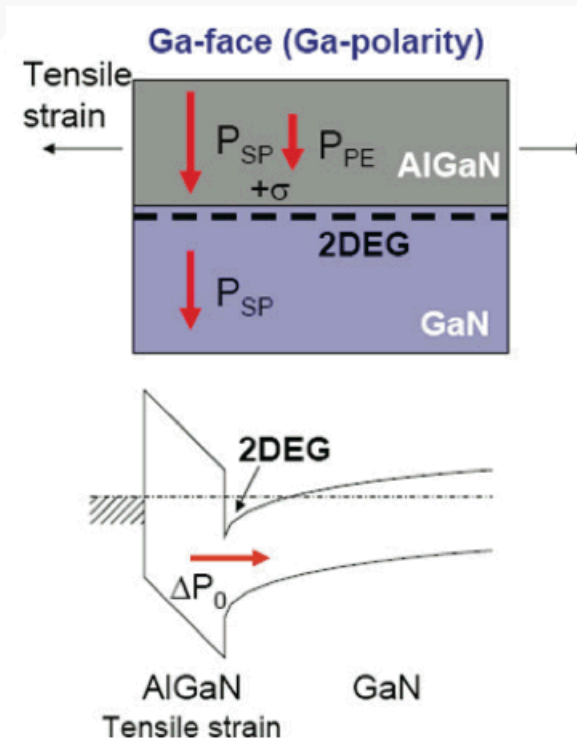
- Low  $V_{CE}$ : MOSFET in series with diode
- Higher  $V_{CE}$ : MOSFET-controlled BJT;  
 $I_{BJT} = (1 + \beta_{BJT}) I_{MOSFET}$
- Diode voltage offset is undesirable due to increased power dissipation
- Parasitic thyristor structure can cause latch-up if not properly accounted for



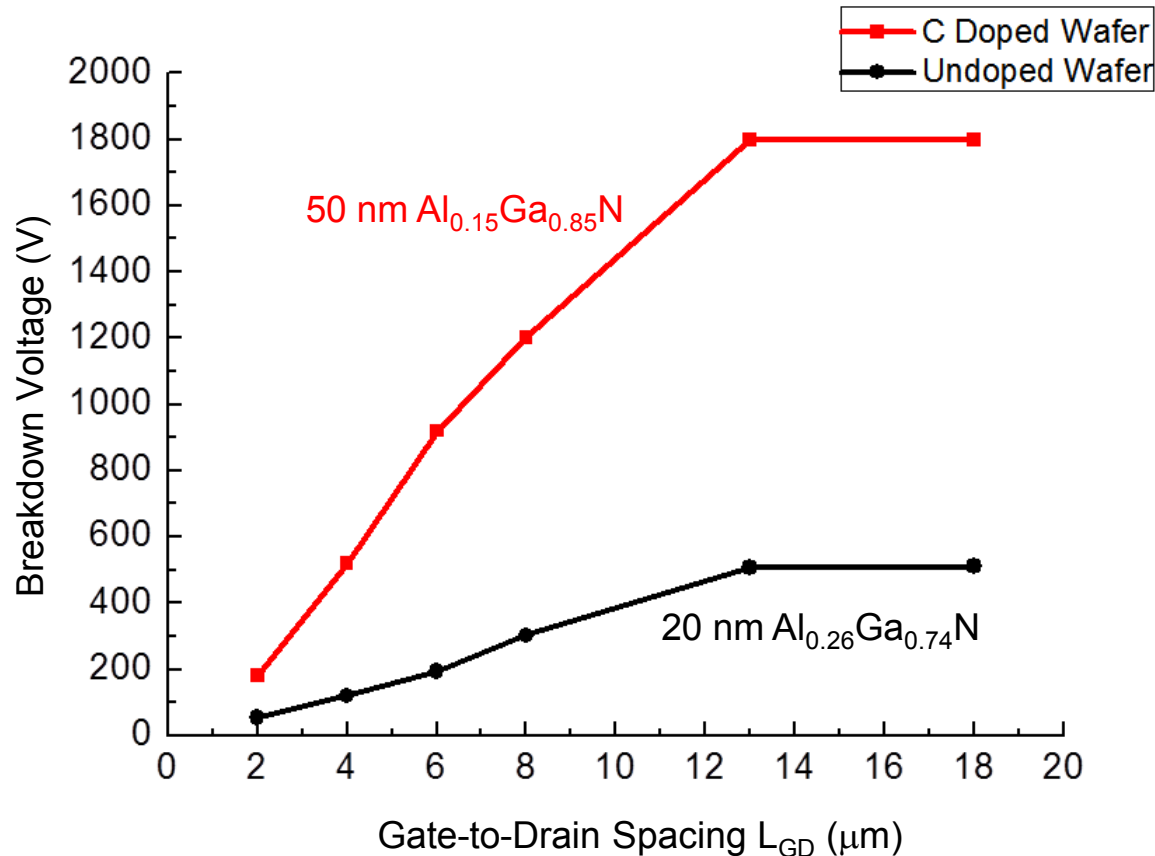
# AlGaN/GaN High-Electron Mobility Transistor (HEMT)



- Power switching HEMT has evolved from AlGaN/GaN microwave HEMT
- Polarization induces high- $\mu$  channel without doping (i.e. no scattering)
- Normally-on device (more complex normally-off designs are possible)
- High field is dropped laterally; field is very non-uniform in channel (peaked near gate edge) and field plates are employed to mitigate this problem



# GaN Initiative for Grid Applications (collaboration with T. Palacios at MIT)



Goal is a Grid-level lateral HEMT

$L_G = 2 \mu\text{m}$ ,  $L_{GS} = 1.5 \mu\text{m}$ ,  $L_{GD} = 1.5$  to  $40 \mu\text{m}$

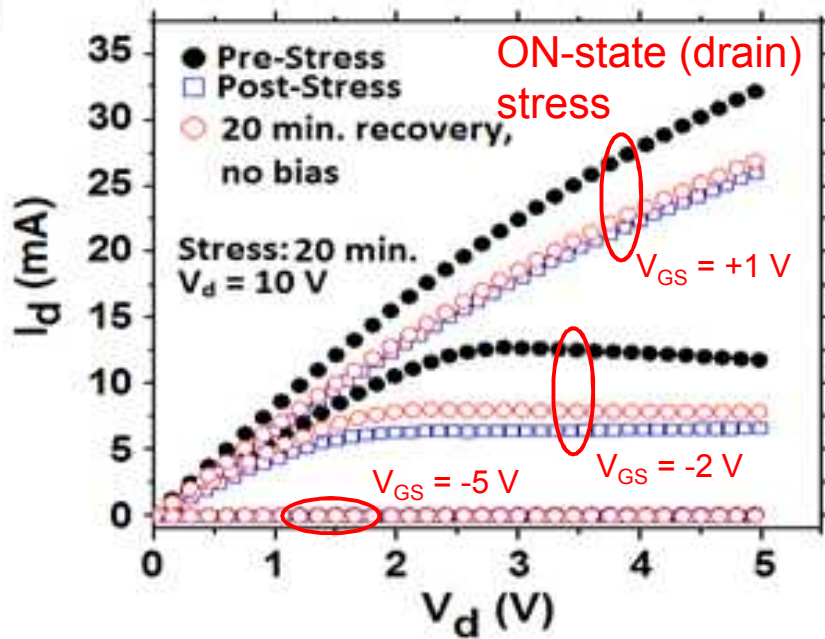
All devices grown on (111) Si by MOCVD



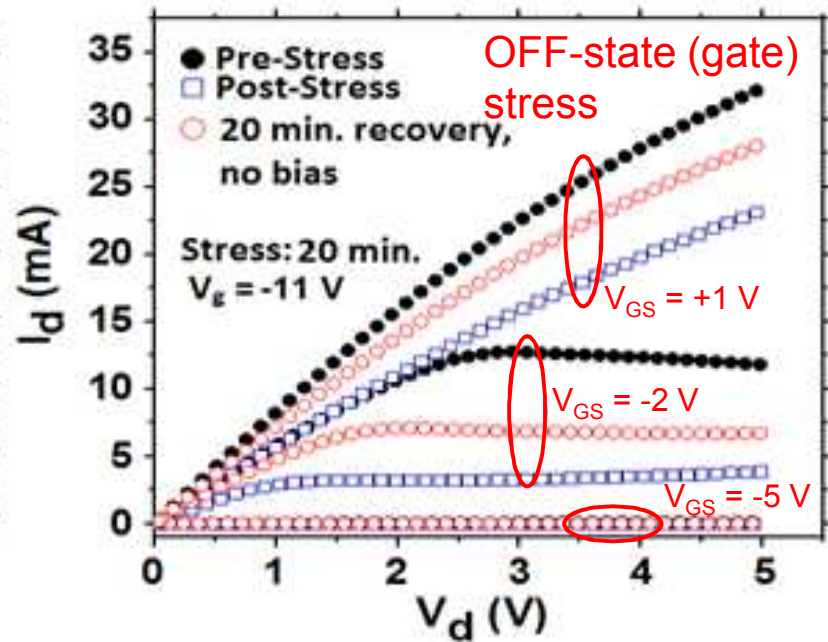


# ON-State vs. OFF-State Stress

Passivated  $\text{Al}_{0.15}\text{Ga}_{0.85}\text{N}/\text{GaN}$  sample



Stress:  $V_{DS} = 10$  V,  $V_{GS} = 0$  V (ON)

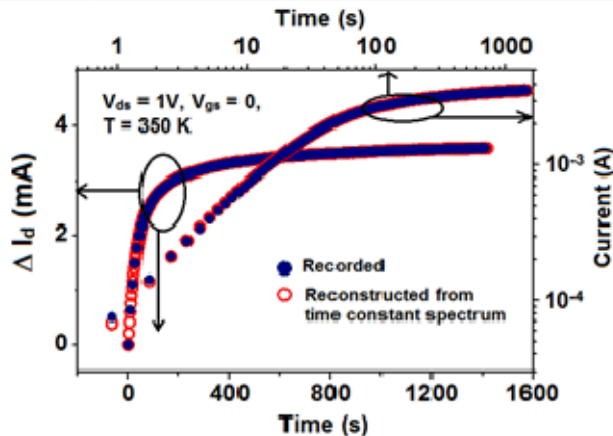


Stress:  $V_{DS} = 0$  V,  $V_{GS} = -11$  V (OFF)

ON-state stress (drain bias) results in much slower recovery than OFF-state stress (gate bias)



# Recovery Current Transient Analysis Following Gate Stress

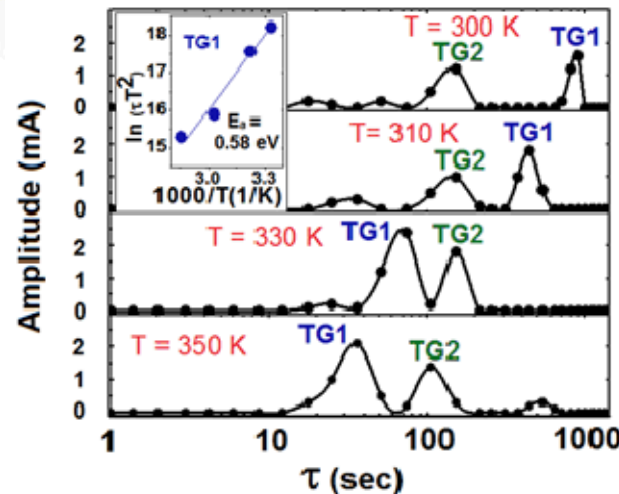


Fitting of recovery transient amplitudes

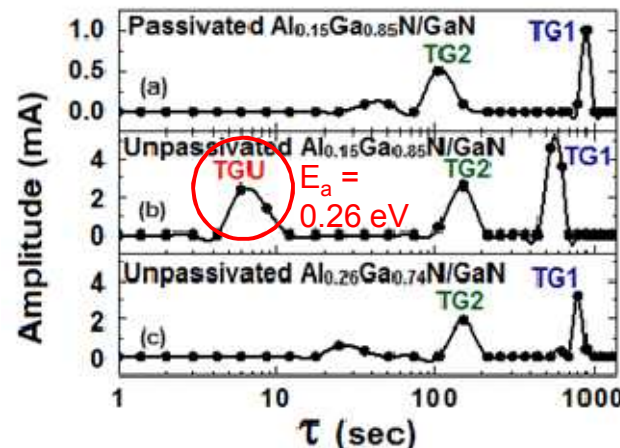
$A_i$  with fixed  $\tau_i$ :

$$\Delta I_d = \sum_i A_i \left[ 1 - \exp\left(-\frac{t}{\tau_i}\right) \right]$$

Peaks in time constant spectra are indicative of different traps in different samples



Passivated  $\text{Al}_{0.26}\text{Ga}_{0.74}\text{N}/\text{GaN}$  temperature dependence

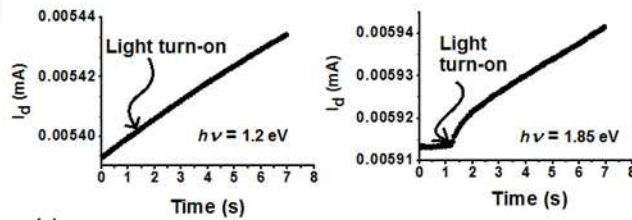


Comparison of other samples



# Optical Recovery of Drain-Stress-Induced Trap

15% Al

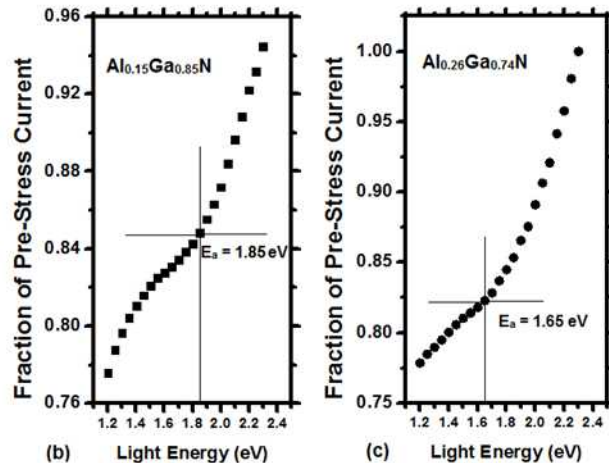


(a)

7 s exposure  
at each  $\lambda$

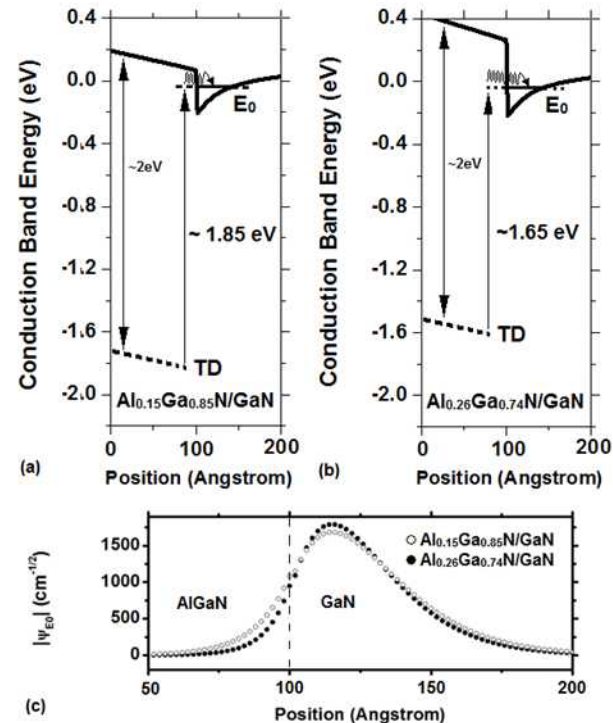
$$V_{DS} = 1 \text{ V}$$

$$V_{GS} = 0 \text{ V}$$



(b)

(c)



(a)

(b)

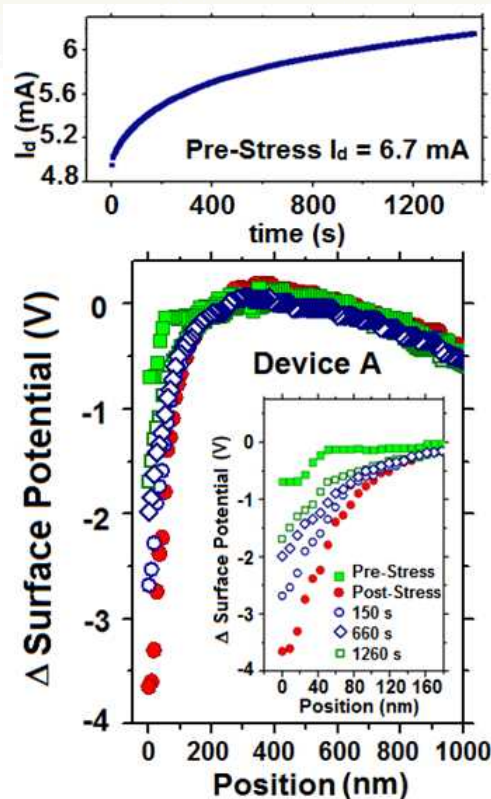
(c)

Inflection point ( $d^2I/dE^2$ ) depends on barrier composition; consistent with transition from a deep level  $E_c - 2.0$  eV in the AlGa<sub>N</sub> to the 2DEG



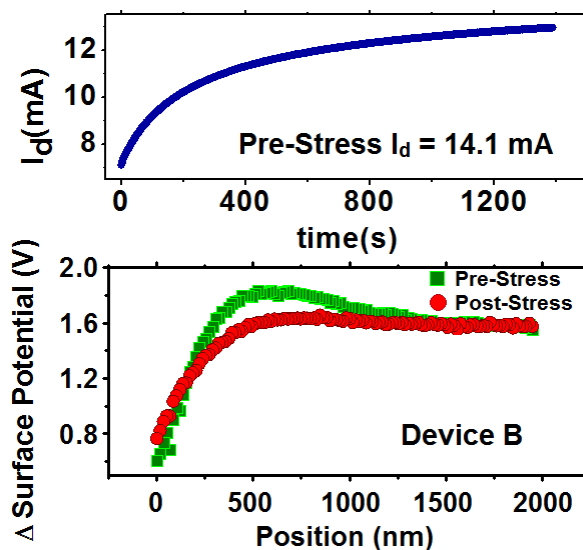


# Correlated Surface Potential and Drain Current Following Gate Stress



**Device A:** Large change in surface potential near the gate edge

Device type	AlGaN Barrier	GaN Buffer	Passivation
A (1)	50 nm $\text{Al}_{0.15}\text{Ga}_{0.85}\text{N}$	Carbon doped	ALD deposited $\text{Al}_2\text{O}_3/\text{SiO}_2/\text{Al}_2\text{O}_3$
B (4)	20 nm $\text{Al}_{0.26}\text{Ga}_{0.74}\text{N}$	Undoped	None



**Device B:** Negligible change in surface potential throughout the drain extension

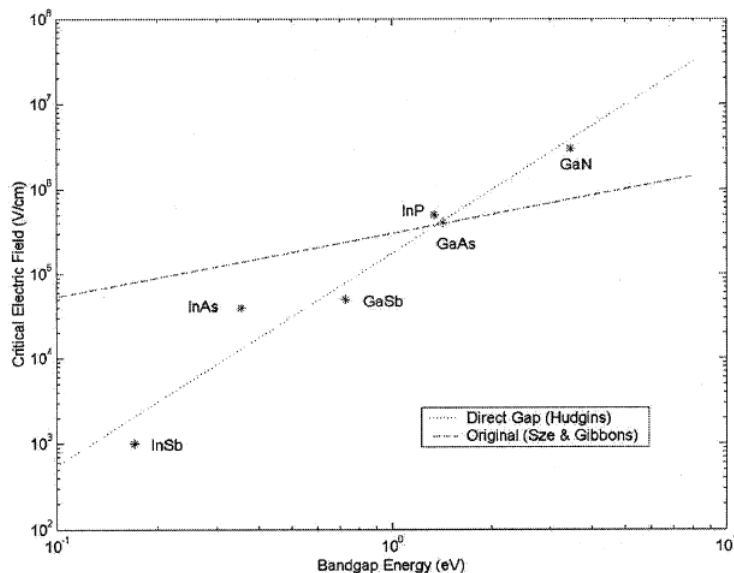
**Results inconsistent with expectations based on buffer doping and surface passivation**

S. DasGupta et al., *Applied Physics Letters* **101**, 243506 (2012)





# Ultra-Wide-Bandgap Materials for Orders-of-Magnitude Performance Improvement



Hudgins et al., TED **18** (3), 907 (2003).

Postulated dependence of  $\epsilon_C$  on  $E_G$  for direct gap materials:

$$\epsilon_C \sim E_G^{2.5}$$

$$E_G(\text{AlN})/E_G(\text{GaN}) = 6.2/3.4 = 1.8$$

$$\epsilon_C(\text{AlN})/\epsilon_C(\text{GaN}) = 1.8^{2.5} = 4.3$$

Remember unipolar FOM:

$$\text{FOM} = V_B^2/R_{\text{on,sp}} = \epsilon\mu\epsilon_C^3/4$$

$$\text{FOM}(\text{AlN})/\text{FOM}(\text{GaN}) = 4.3^3 \approx 80!$$

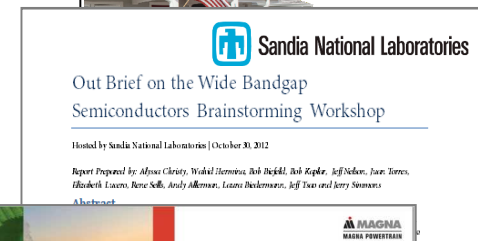
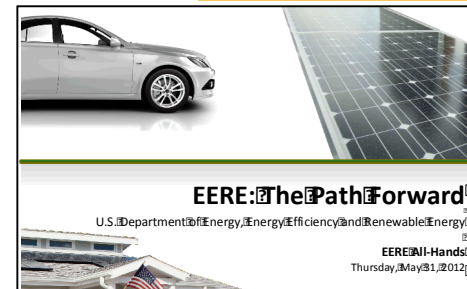
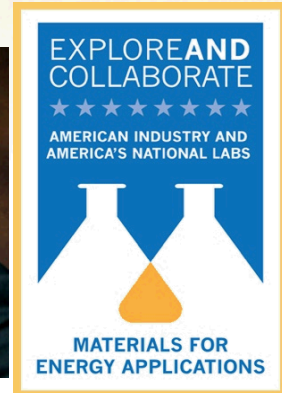
This assumes equal electron mobility, which is probably not true; *nevertheless*, increase in  $E_C$  (cubic dependence) likely outweighs decrease in  $m$  (linear dependence)

Material growth issues are of paramount importance, similar to GaN but less mature



# Increasing DOE Interest in WBGs

- **2010 ARPA-E ADEPT Program:** “Agile Delivery of Electric Power Technology,” \$34.5M
- **Feb 1, 2012:** Chu’s Materials for Energy Applications workshop, Berkeley – *WBGs one of four major topics in Chu’s talk*
- **May 31, 2012:** EERE—New undersecretary David Danielson announces WBG’s as one of his four major initiatives
- **June 26, 2012:** **SNL Workshop on Power Electronics**
- **July 25, 2012:** **WBG Semiconductors for Clean Energy Workshop** (Dave Danielson, DOE/AMO Invitation-only)
- **Sept. 11 and Oct. 23, 2012:** **Robust WBG Semiconductor Power Electronics Workshops** (ANL and the University of Maryland)
- **October 30, 2012:** **SNL WBG Semiconductors Brainstorming Workshop** - *Outlined a Center concept for review from participants*
- **Nov. 15-16, 2012:** **Automotive Wide Bandgap Devices and Applications** (Oak Ridge National Laboratory)
  - *Wide Bandgap devices for the next generation of electric drive systems*



# The Need for a National WBG Center

## A National Center for Innovation in Wide-Bandgap Semiconductors would

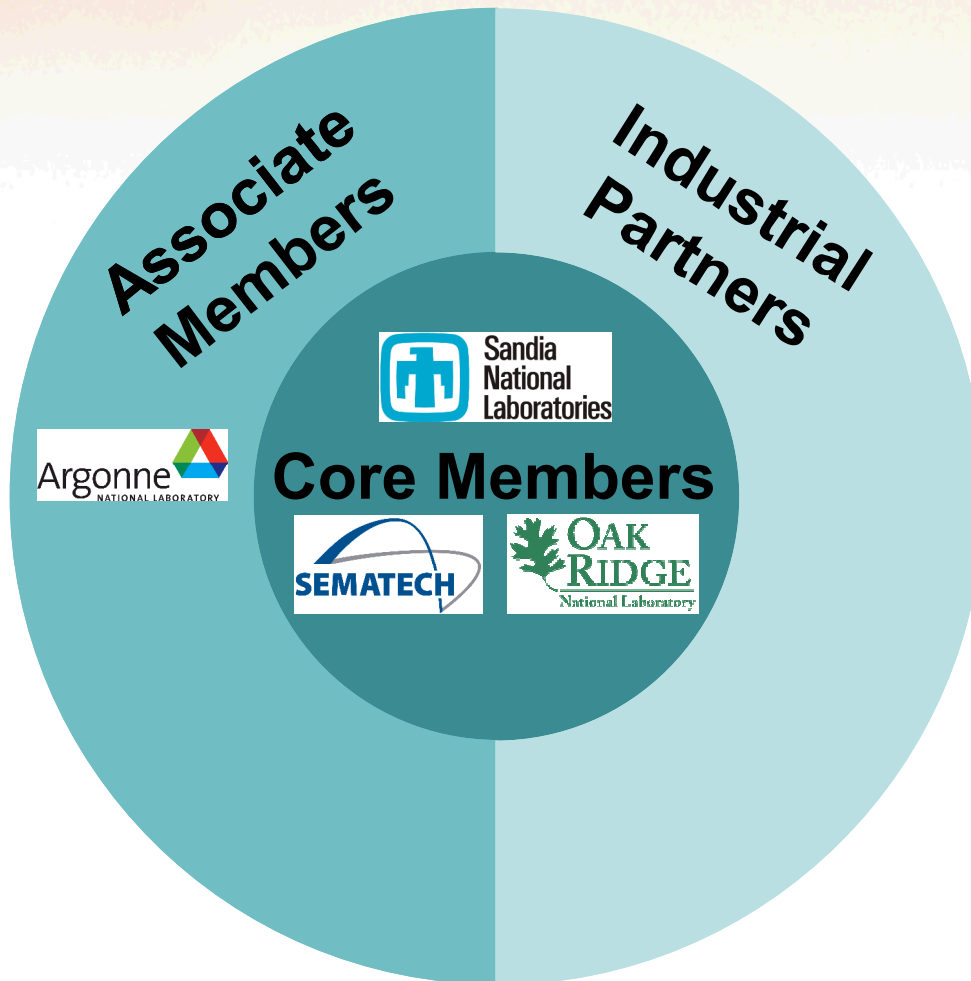
- Spur innovation and enhance competitiveness of U.S. industry
- Improve energy efficiency and incorporation of renewable energy sources
- Enable intelligent, resilient energy grids

## This center would build on Sandia's established excellence in

- III-N WBGs for solid-state lighting
- Fabrication, testing, and failure analysis at MESA and CINT
- PV reliability at DETL and microgrid GC LDRD
- Existing power electronics work (energy storage program)



# Proposed Center Structure



## Core Members (3):

Collectively possess a suite of capabilities unique in its degree of vertical integration and its ability to support collaboration at any level of the technology innovation chain.

## Associate Members (~5-10):

Non-profits who will contribute their complimentary capabilities to the Center.

## Industrial Partners (~15-20):

- **Industrial Collaborators** drive the Center's response to industrial needs
- **Industrial Users** utilize Center resources to enhance US industrial competitiveness





# National Center Technical Scope

## Wide Band Gap Center Activities



# Summary

- **WBG power devices promise to increase efficiency and reduce system complexity, but materials and reliability issues have hampered their adoption**
- **Sandia possesses a full range of WBG capabilities spanning from fundamental materials science to grid-level power systems, and is well-positioned to address these outstanding problems**
- **WBG power device work to date has been funded by DOE OE and has focused on SiC and GaN power device reliability; parallel work funded by DOE EERE has examined PV inverter reliability**
- **An opportunity exists to establish a DOE EERE-sponsored “national center” of excellence, in conjunction with other partners (Oak Ridge, Sematech, Argonne, etc.)**

